Remaining Topic

- Semiconductor Memory
  - Overall structure of DRAM and SRAM
  - Flash memory

Classifications

	Volatile	Speed	Density
SRAM	Yes	High	Moderate
DRAM	Yes	Moderate	High
ROM	No	High	Moderate
EPROM	No	Low	Low
Flash	No	Low	High
MRAM	No	High	Moderate
FeRAM	No	High	Moderate

“Ware-out” Issue

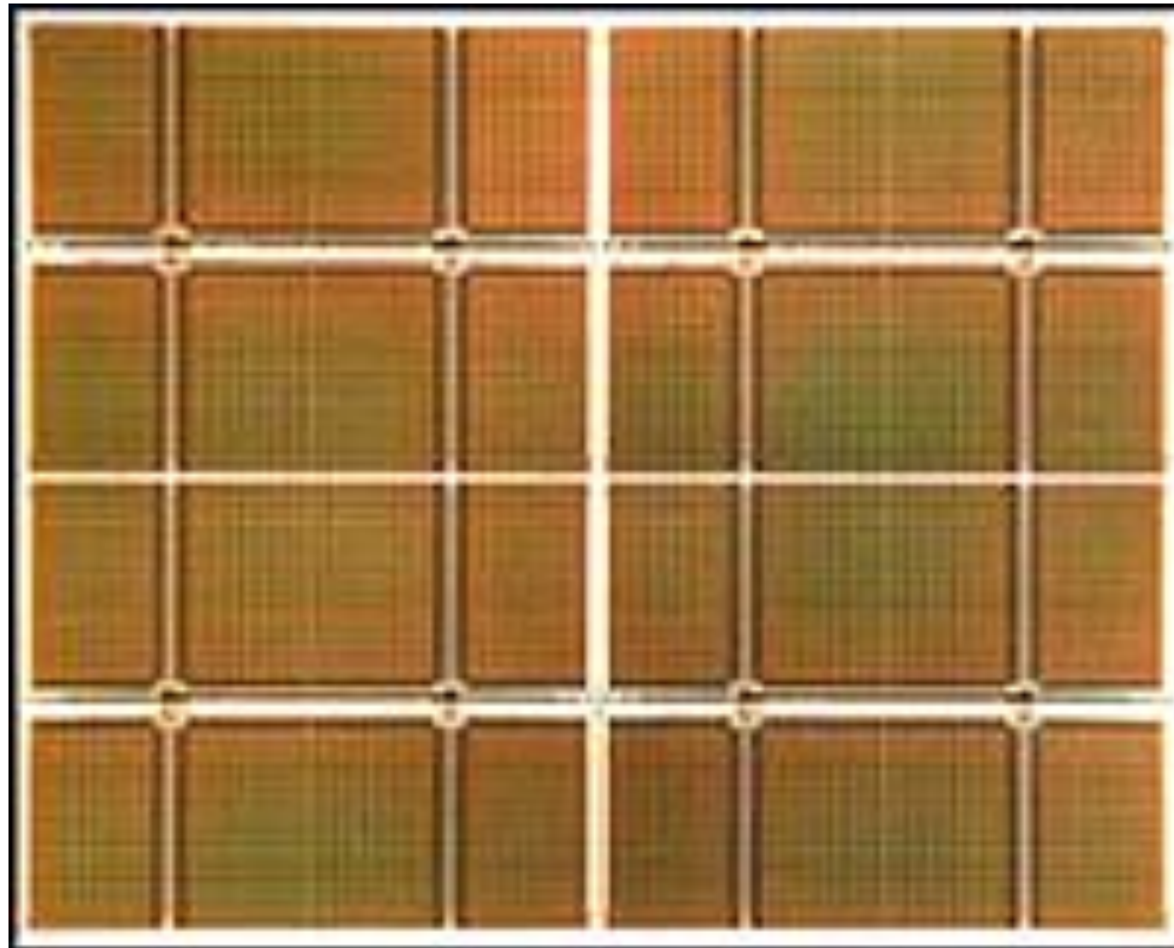
	Volatile	Speed	Density
SRAM	Yes	High	Moderate
DRAM	Yes	Moderate	High
ROM	No	High	Moderate
EPROM	No	Low	Low
Flash	No	Low	High
MRAM	No	High	Moderate
FeRAM	No	High	Moderate

Memory Classification

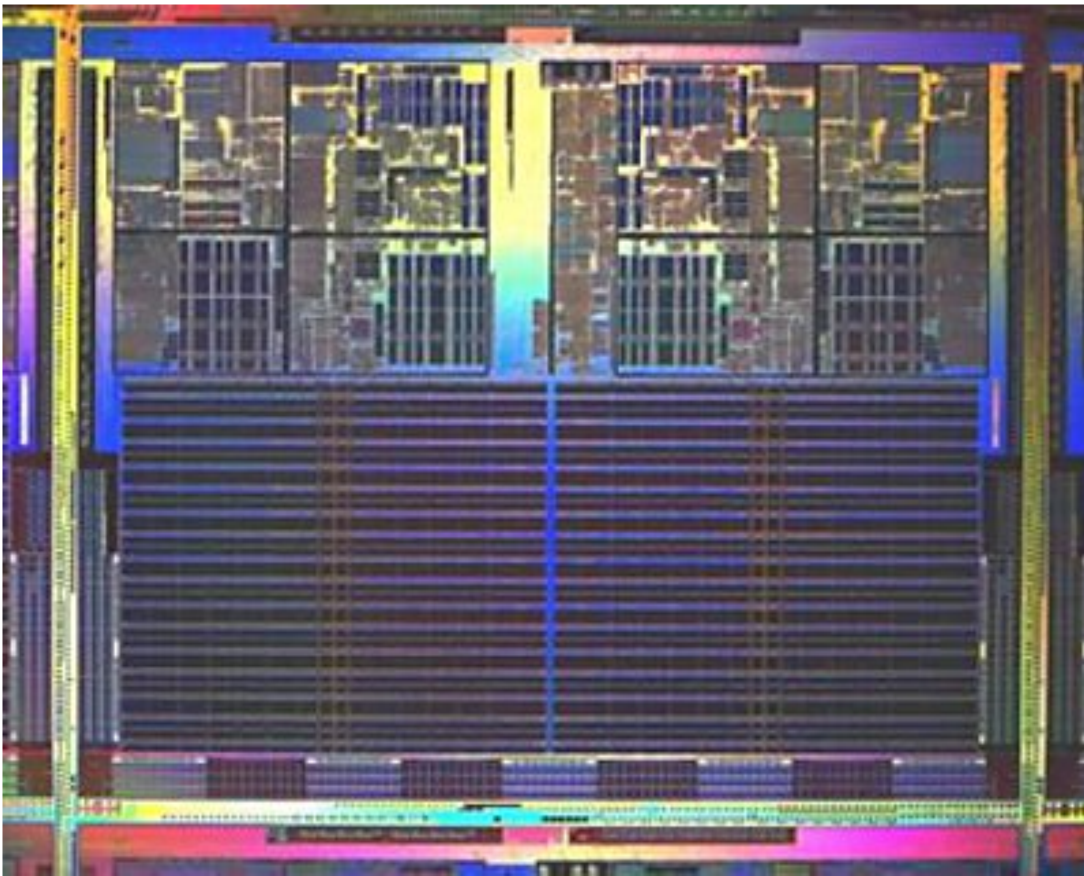
Stand Alone Memory
- DRAM, ROM, SRAM, FLASH, EPROM
- MRAM, FeRAM

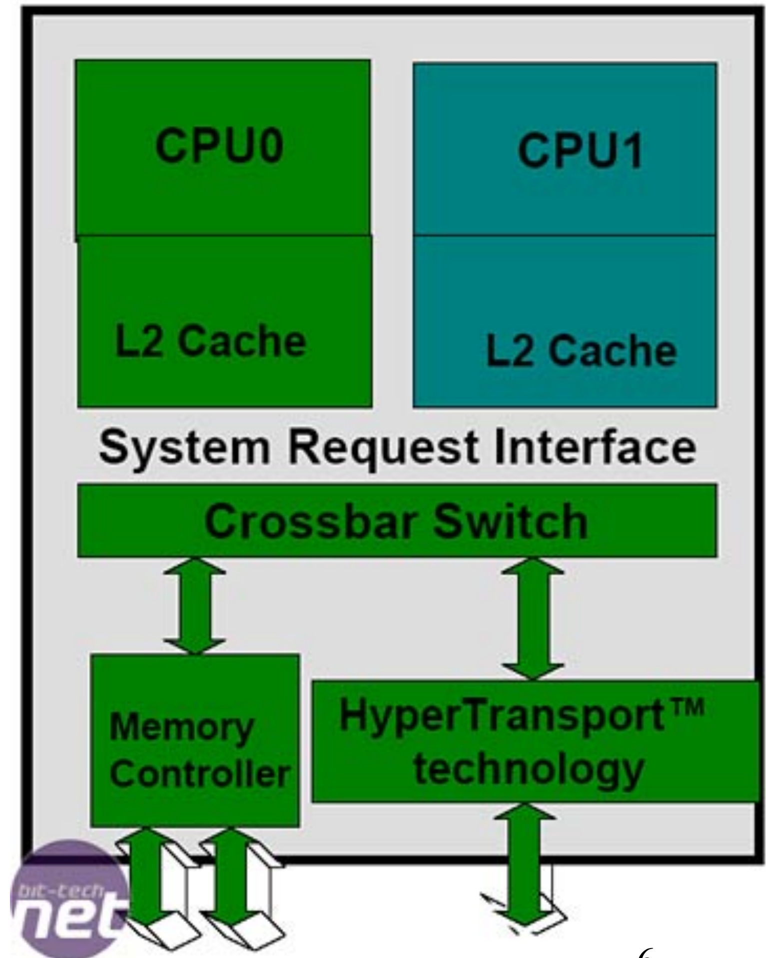
Embedded Memory
- SRAM for cache
- DRAM
- ROM

4Gb DRAM



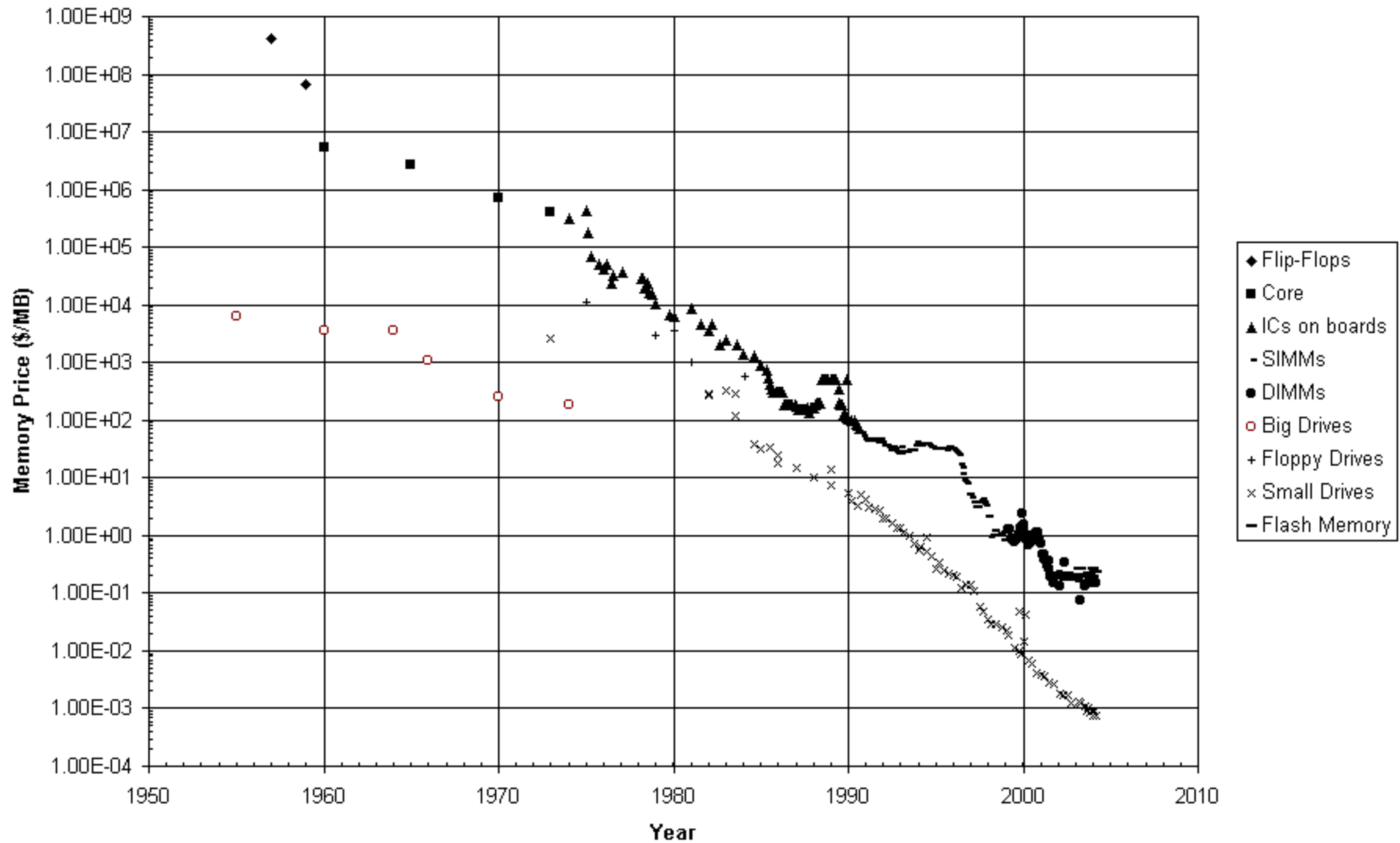
AMD Dual-Core Athlon





Memory Market

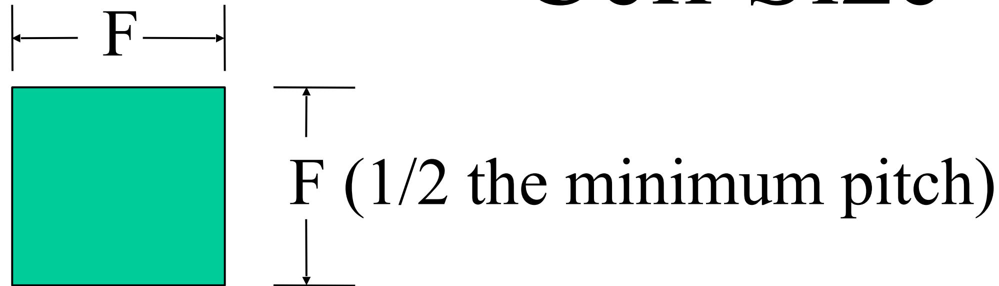
SIA Memory Market Summary

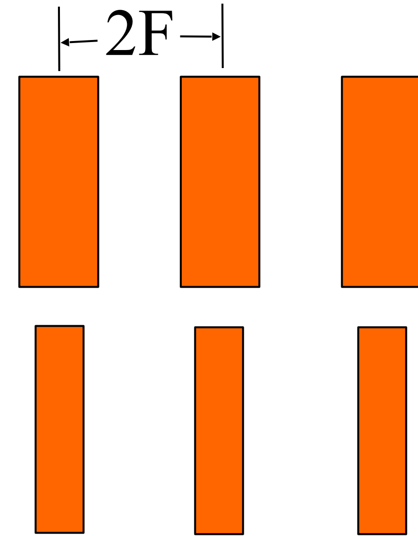


http://www.jcmit.com/mem2002.htm

Memory Density

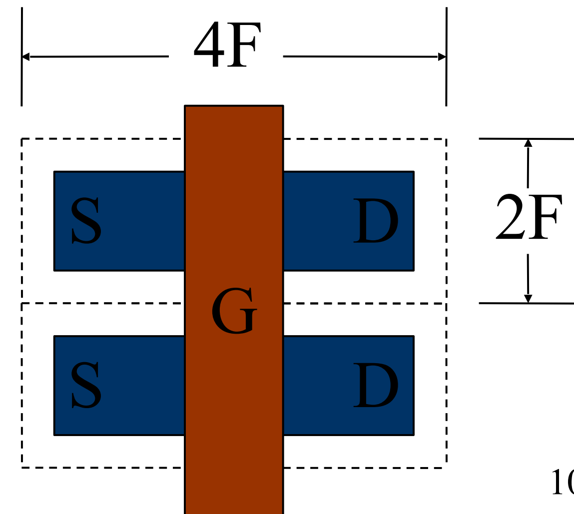
Cell Size





SRAM 6-T cell:
40-100 F^2 cell

DRAM 1-T, 1-C cell:
5-10 F^2 cell; most common $8F^2$ cell



Memory Circuits

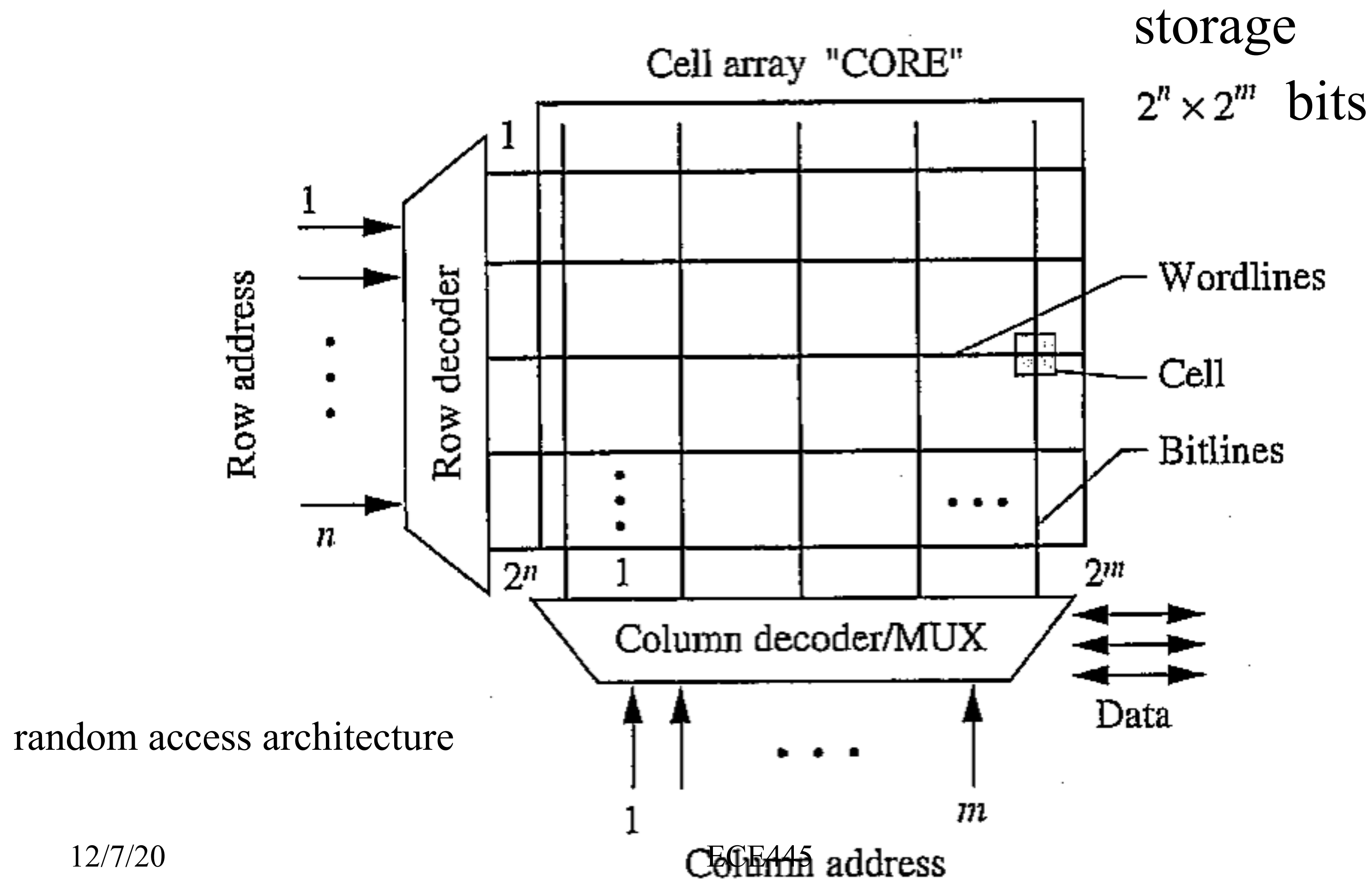
Memory Core - typically stores 1-bit
- can have multilevel cores)

Peripheral Circuits
- row and column decoders
- sense amplifiers
- column precharge circuits
- data buffers
- read/write (R/W) circuits
- …

Typical Memory Organization

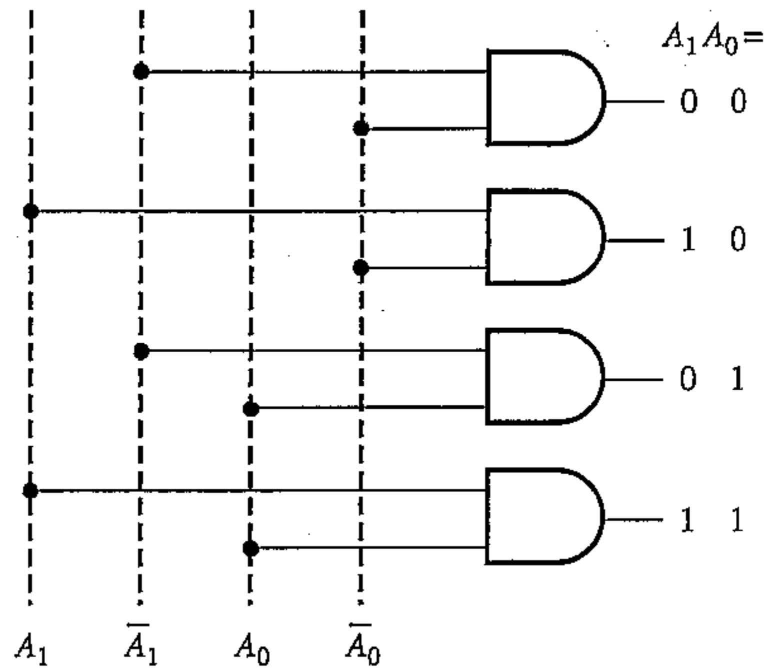
storage

$2^n \times 2^m$ bits

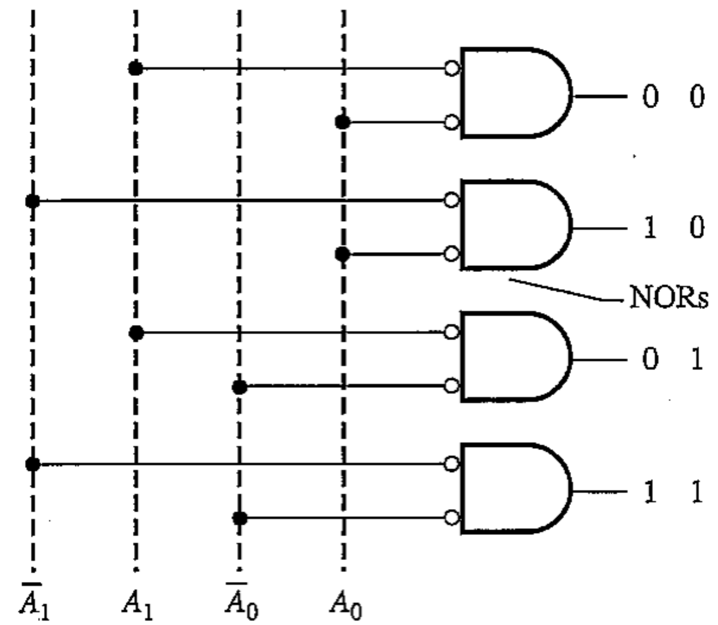


random access architecture

Row Decoder (n=2)



(a) AND-based decoder



(b) NOR-based decoder

Cascade Decoder

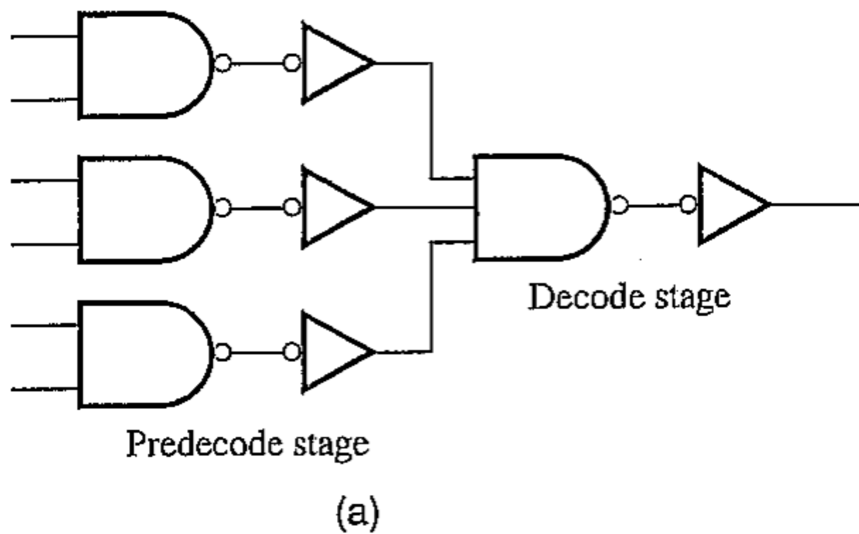
An n-bit decoder → 2^n logic gates each with n inputs

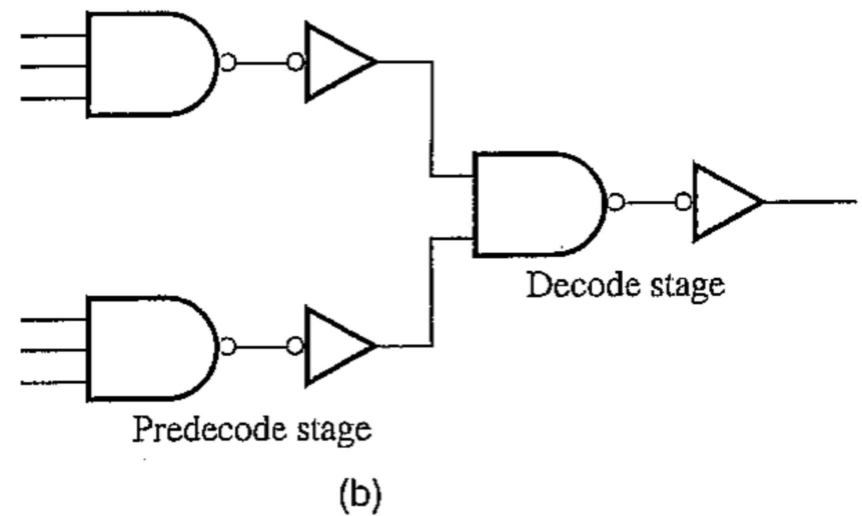
For n=6 → requires 64, 6–input NAND gates and 64 Inverters

To minimize delay caused by large series resistances → cascade
- predecode stage
- final decode stage

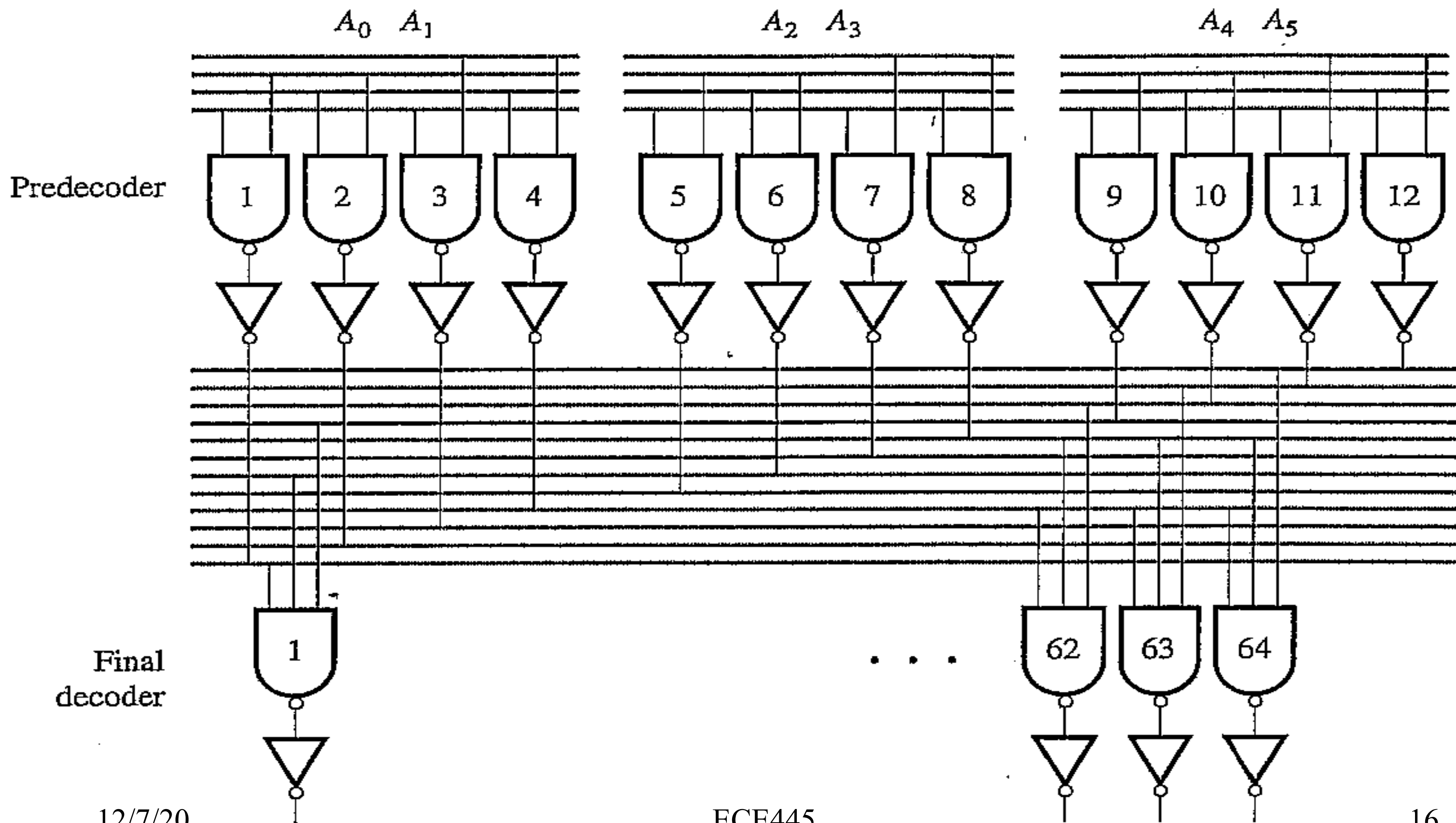
Allows intermediate signals from the predecode stage to be reused by the final decoding stage

Alternative 6-input NAND

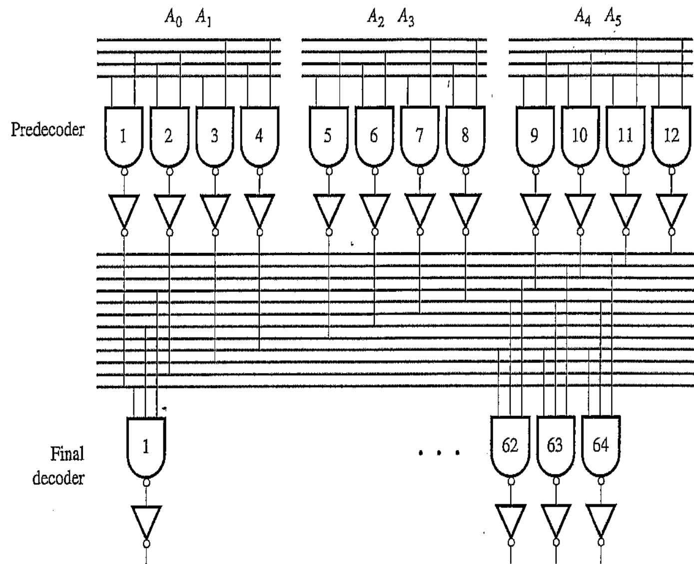




Reuse of Intermediate Signals



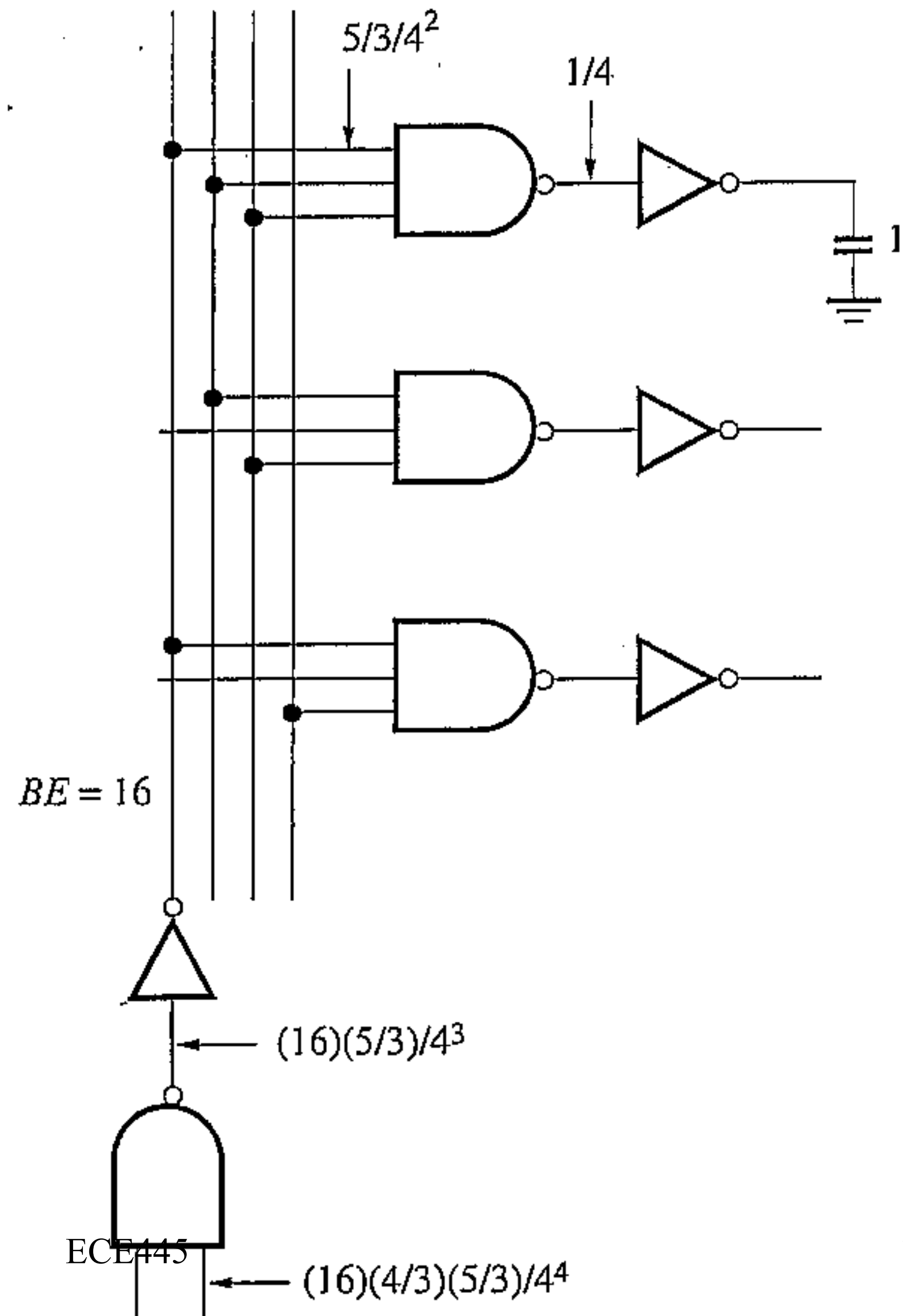
Sizing Using Logical Effort



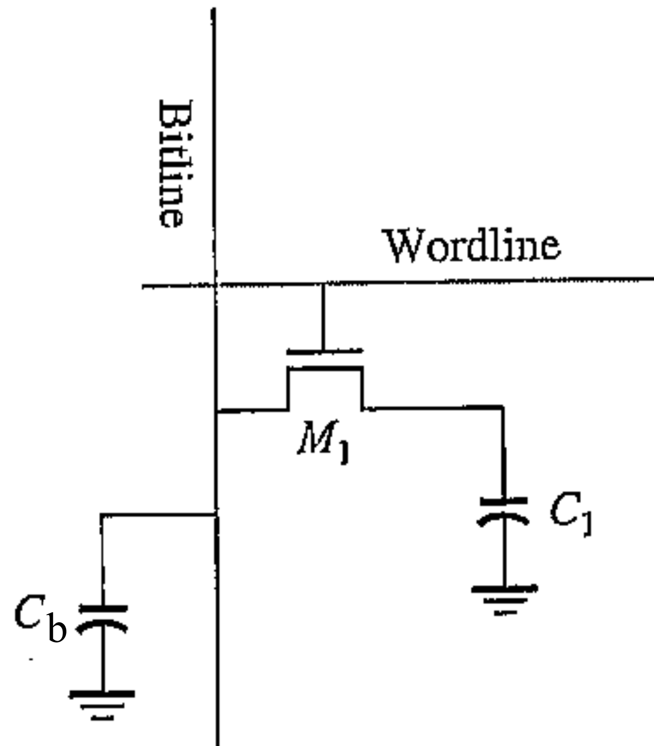
Size the decoder assuming:
- normalized output load = 1
- fan-out = 4

Work backwards from the output to the input:
- Normalized output has a size =
- Inverter input capacitance =
- The Logical Effort of the 3-input NAND =
- Input capacitance of 3-input NAND =
- Branching effort at output of predecoder =
- Input capacitance of the inverter =
- The 2-input NAND has an input capacitance =

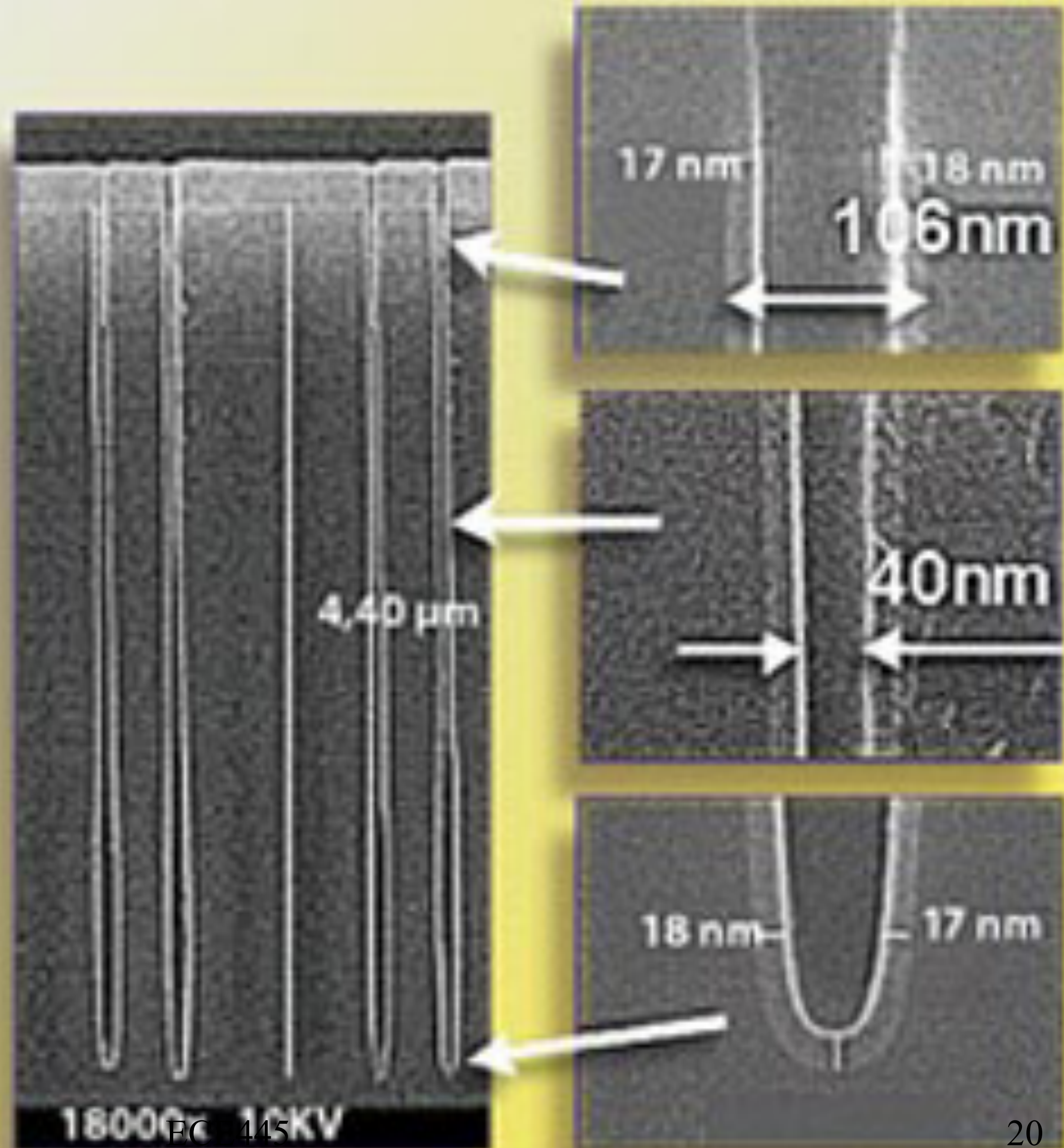
Decoder Size by Logical Effort



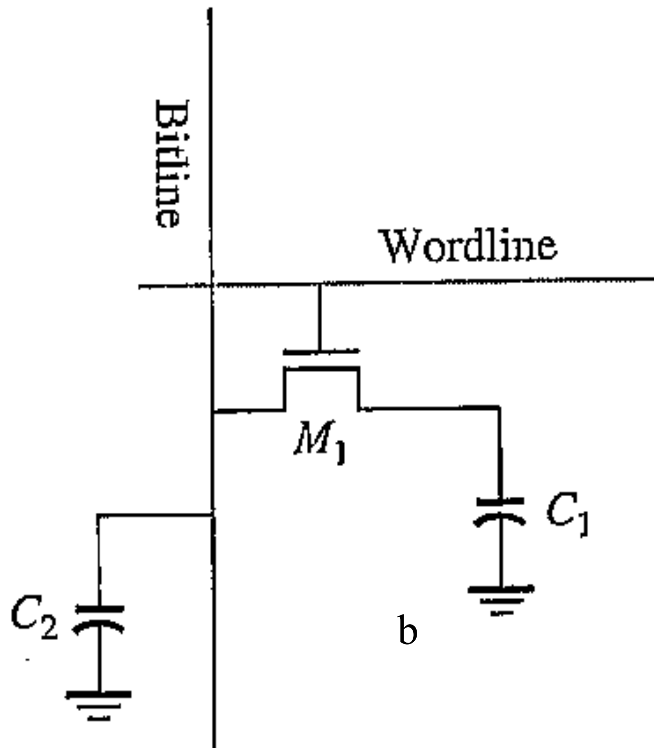
1T DRAM Cell



DRAM Trench Capacitor

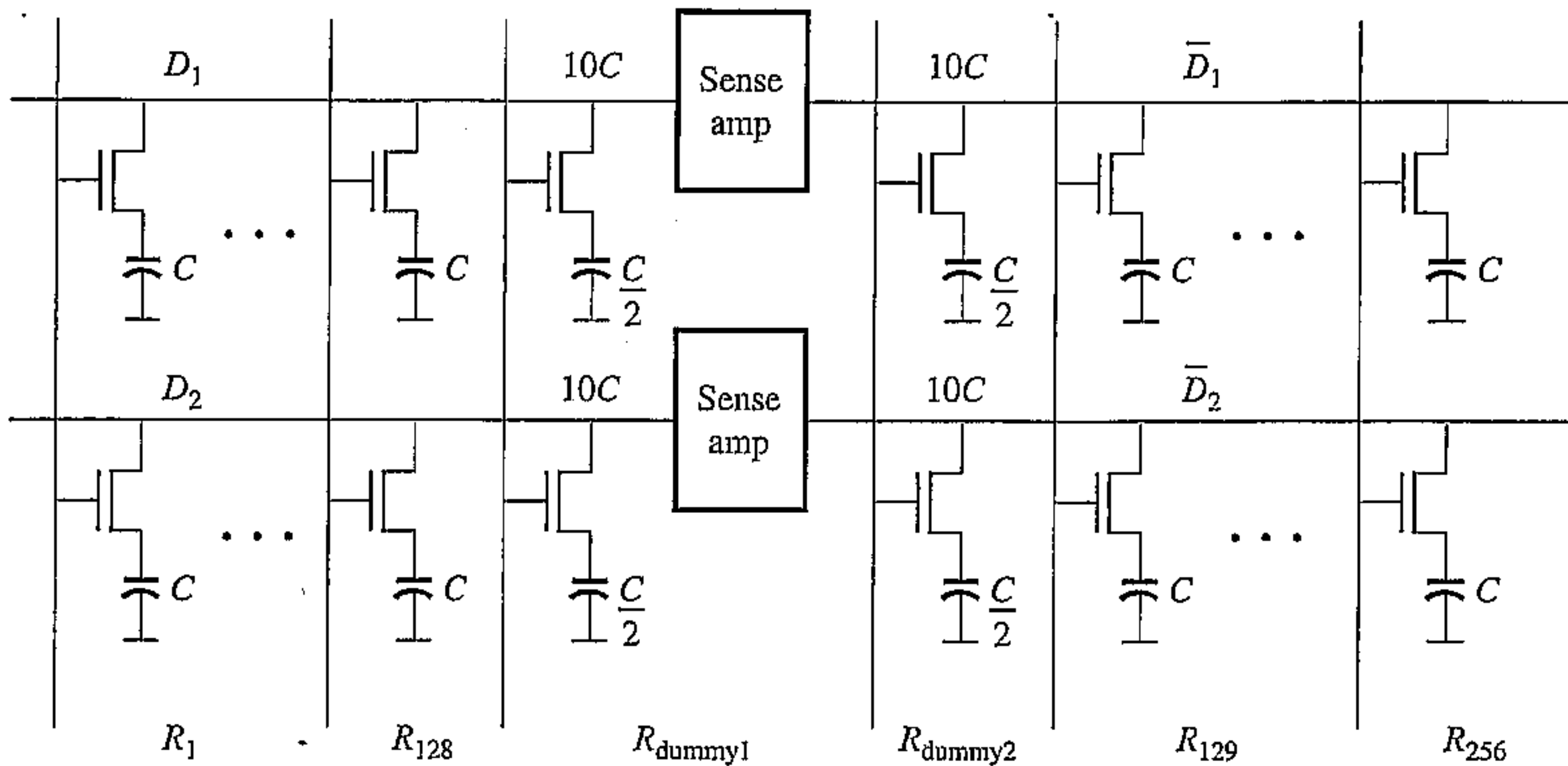


DRAM - Dynamic Circuit



- Destructive Read - requires rewrite after every read
- Leakage —> requires refresh cycle

DRAM Array Configuration



Redundancy

Redundancy is always used on standalone DRAMs and frequently for embedded DRAMs.

Implemented via on chip fuses in which fuses are blown either by a laser pulse or by an electrical pulse during wafer test.

Normally a few rows and columns of redundancy are offered on a large DRAM embedded macro. Smaller macros require less redundancy (or no redundancy)

Redundancy can also be implemented to some extent in the logic part of the circuits. To implement a spare decoder, for example, switches can be used that shift all decoder connections by one to bypass the faulty decoder.

Memory Standards

Most memory standards are controlled by the **JEDEC** Solid State Technology Association (Once known as the **J**oint **E**lectron **D**evice **E**ngineering **C**ouncil). JEDEC is the semiconductor engineering standardization body of the Electronic Industries Alliance (EIA), a trade association that represents all areas of the electronics industry and was originally created in 1960 to cover the standardization of discrete semiconductor devices and later expanded in 1970 to include integrated circuits.

JEDEC does its work through its 48 committees/ subcommittees that are overseen by the **JEDEC** Board of Directors. Presently there are about 300 member companies in **JEDEC** including both manufacturers and users of semiconductor components and others allied to the field.

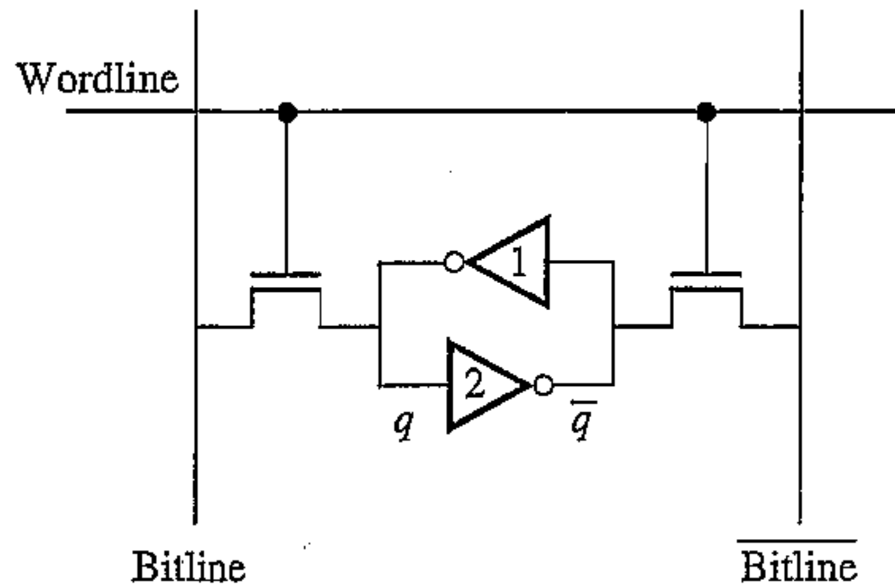
DRAM Architecture

More than 10 Different Types of DRAM

Page Mode DRAM	DRAM
Fast Page Mode DRAM	FPM DRAM
Extended Data Output DRAM	EDO DRAM
Burst Extended Data Output DRAM	BEDO DRAM
Enhanced DRAM	EDRAM
Synchronous DRAM	SDRAM
PC100 Synchronous DRAM	PC100 SDRAM
Enhanced Synchronous DRAM	ESDRAM
Double Data Rate DRAM	DDR DRAM
Direct Rambus DRAM	DRDRAM
Synchronous Link DRAM	SLDRAM

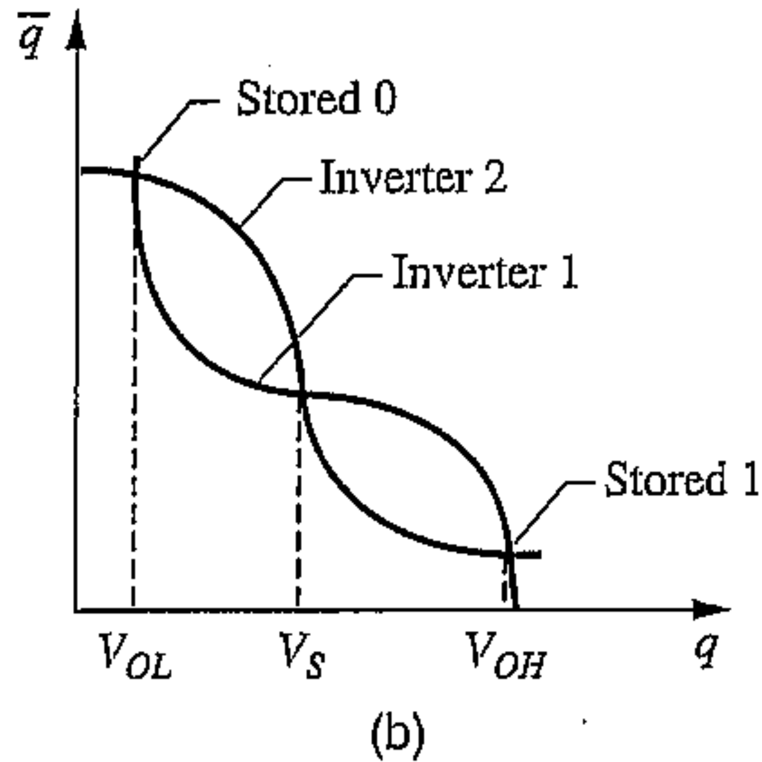
…..

SRAM (Static RAM) Cell

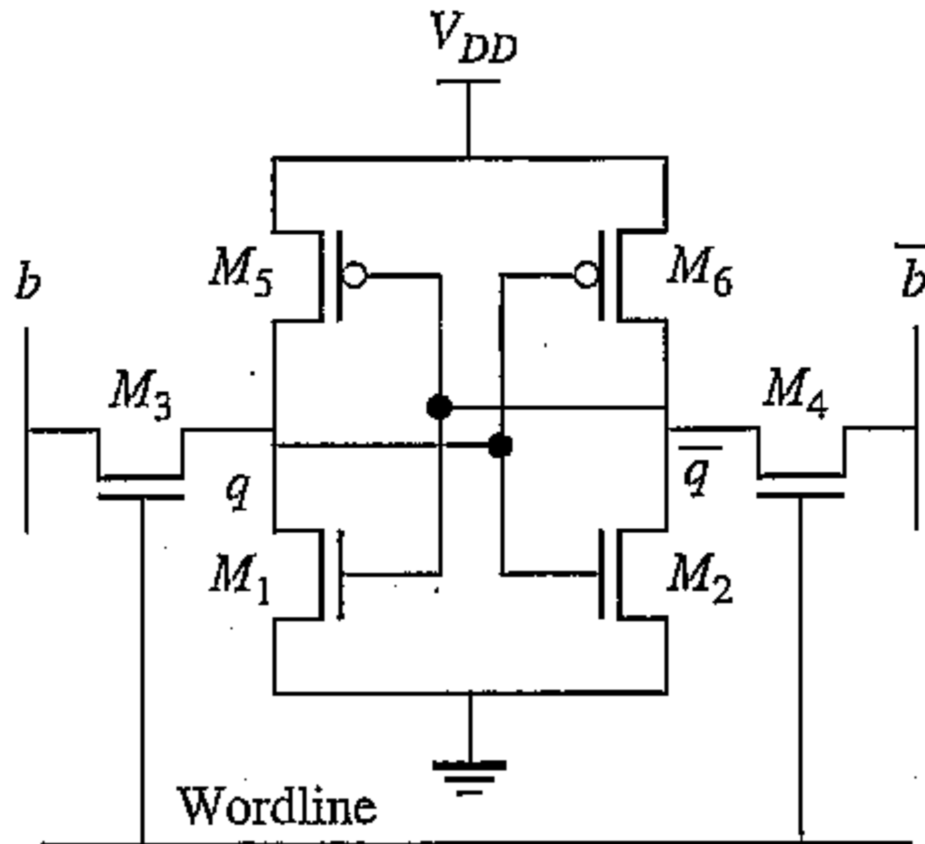


Basic SRAM Cell

Voltage Transfer Characteristics



6-T Configuration



Cell Design Considerations

1. Minimize Cell Area ←→ Increase cell density
   - replace load resistors (M5 and M6) with transistors
   - utilize TFTs for M5 and M6
   - reduce wasted area

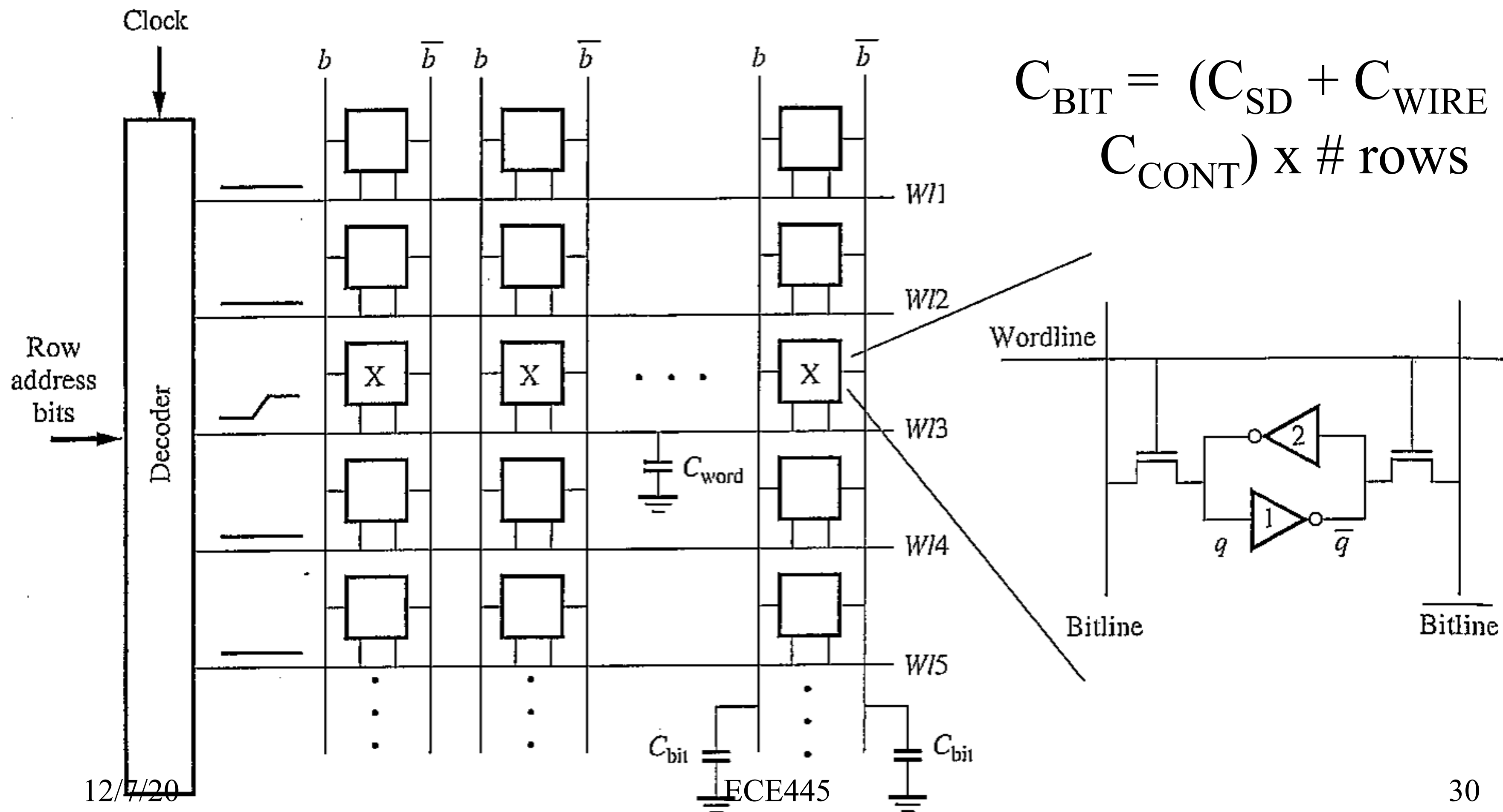
2. Minimize static power → Increase Vt and sub-Vt slope

3. Differential bitlines → improved noise immunity

SRAM Array (simplified)

$C_{WORD} = 2\ (C_G + C_{WIRE})$ x # columns

$C_{BIT} = (C_{SD} + C_{WIRE} + C_{CONT})$ x # rows



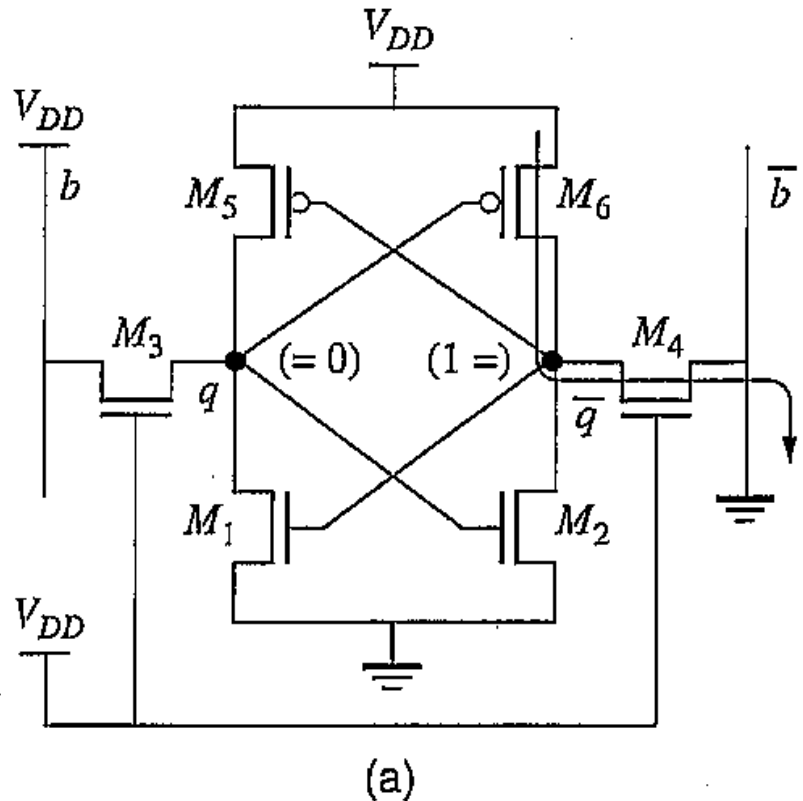
SRAM Read Operation

(a)

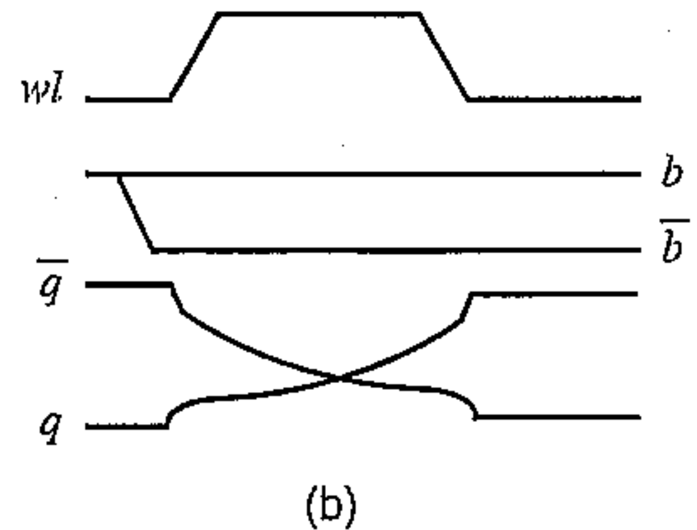
(b)

1. Precharge b, $\overline{b}$ to V_{DD} column pull-up R
2. Turn on wordline to select row
3. CBIT slowly discharges on either b or $\overline{b}$
4. b and $\overline{b}$ → sense amplifier

SRAM Write Operation



(a)



(b)

1. Force either b or $\overline{b}$ low
2. Turn on appropriate word line
3. Node q or $\overline{q}$ is driven low causing the state to switch

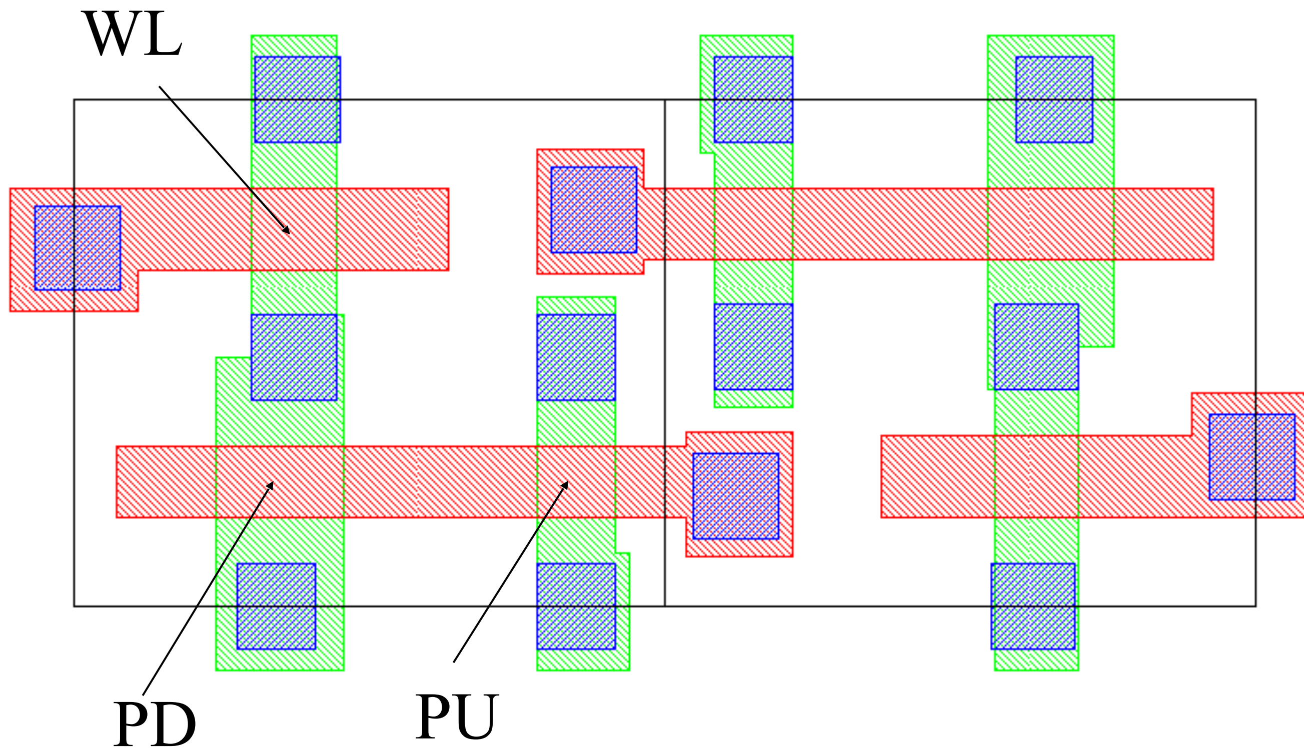
Transistor Sizing Guidelines

1. During read: need to ensure stored value is not disturbed – voltage can not drop below V_S
2. Make conductance of M1, M2 greater than M3, M4
3. Need to supply enough I_{CELL} to discharge C_{BIT} sufficiently in 20-30% of a clock cycle
4. Can estimate I_{CELL}

$$I_{CELL} = C_{BIT} \Delta V / \tau$$

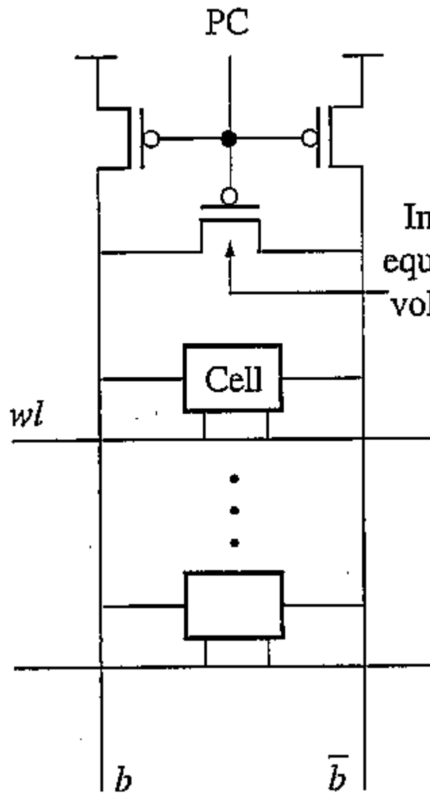
5. During write: make conductance of M3, M4 greater than M5, M6

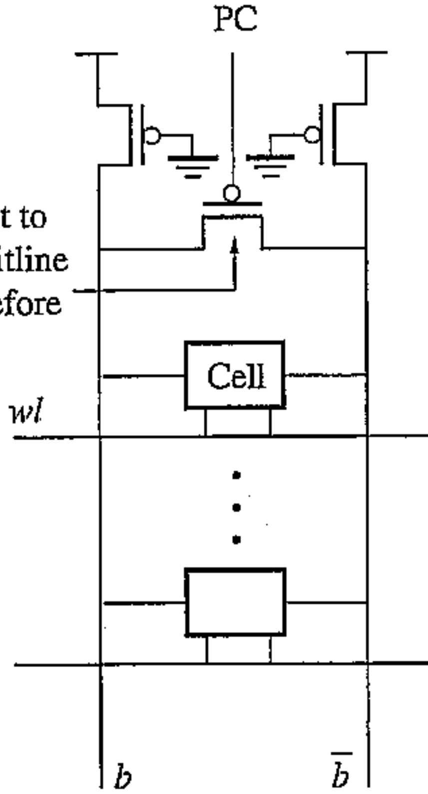
Cell Layout

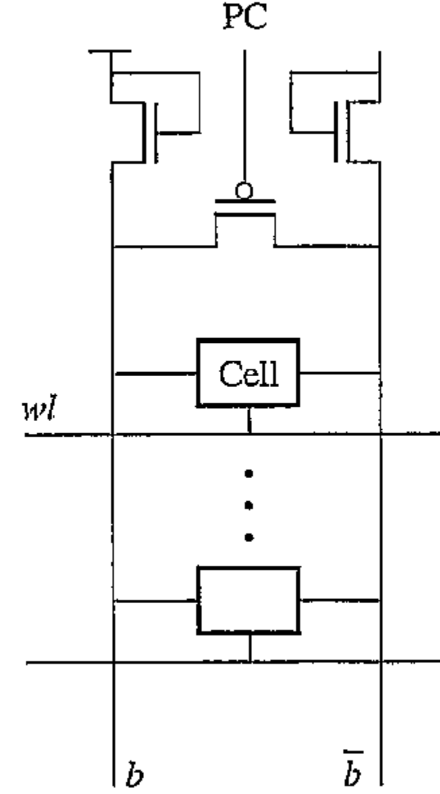


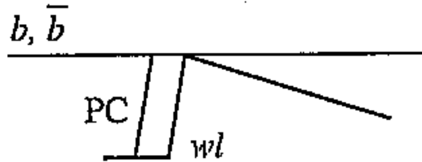
Column Pull-up Circuitry

Dynamic Logic Precharge   Pseudo-NMOS Precharge   NMOS Saturated Enhancement Load

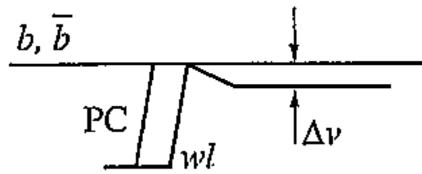




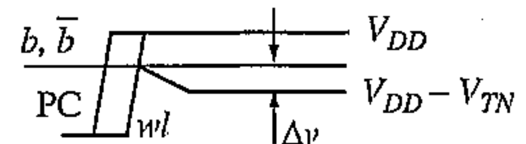




(a)

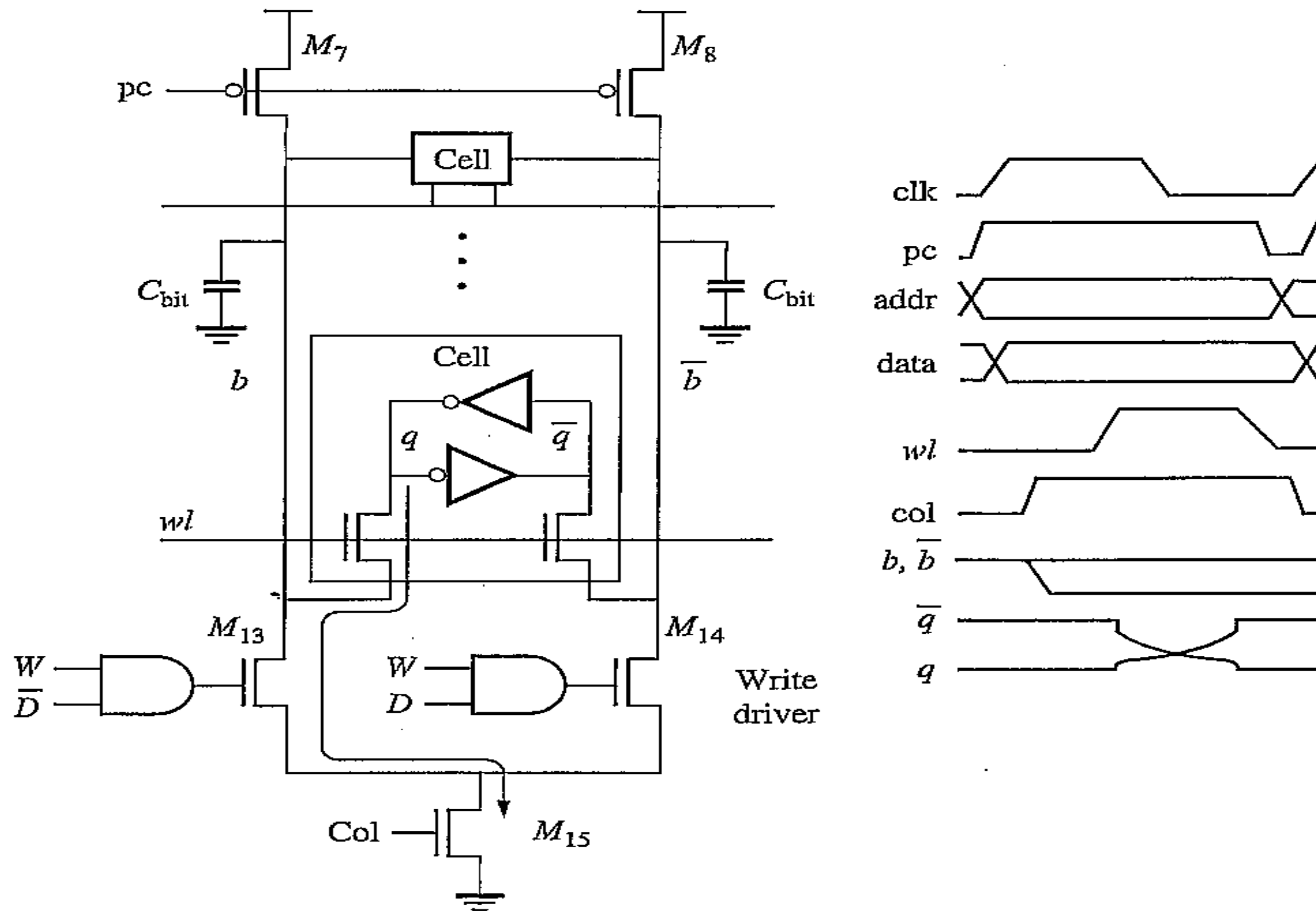


(b)

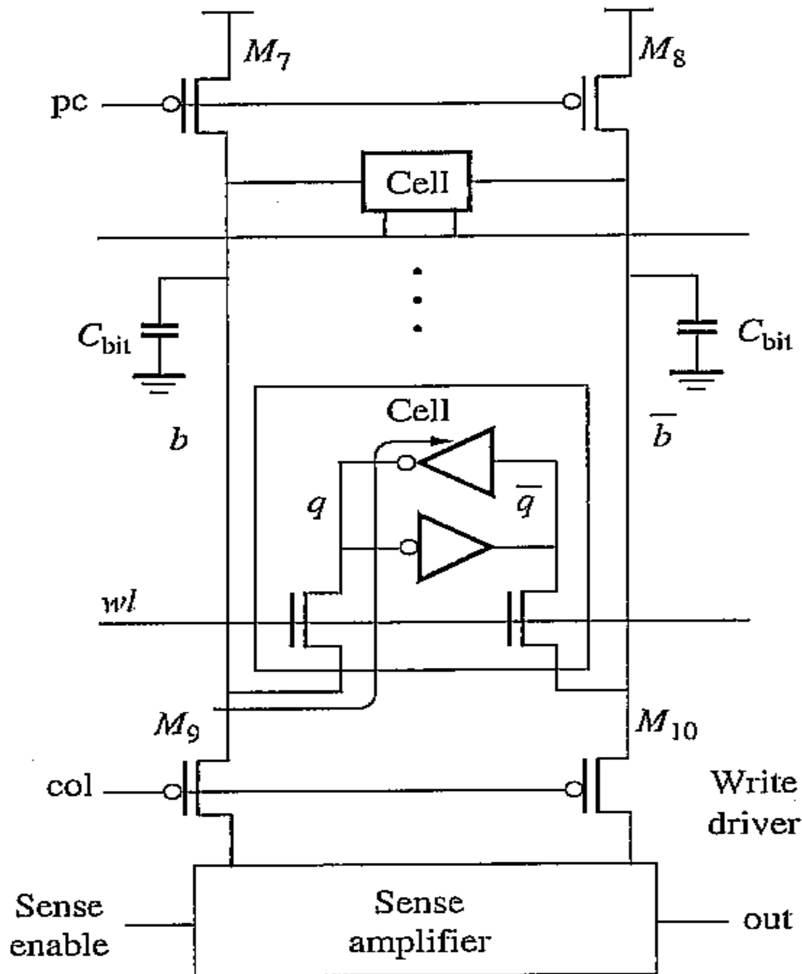


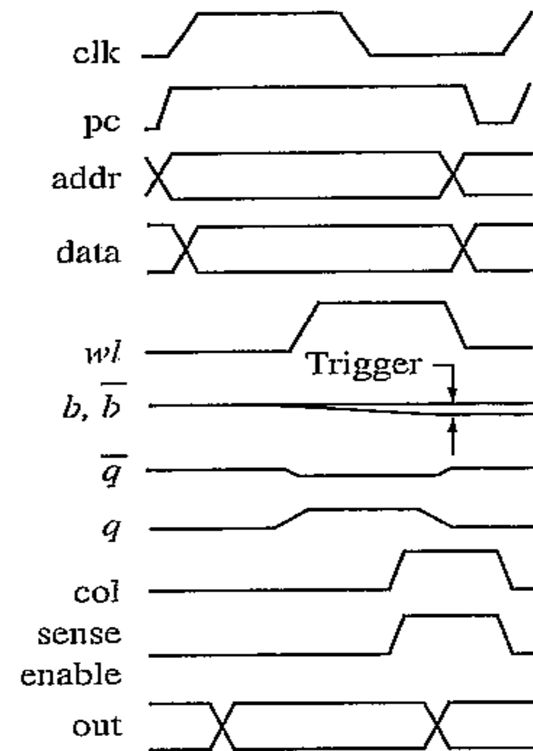
(c)

Write Driver Circuitry



Basic Read Circuitry



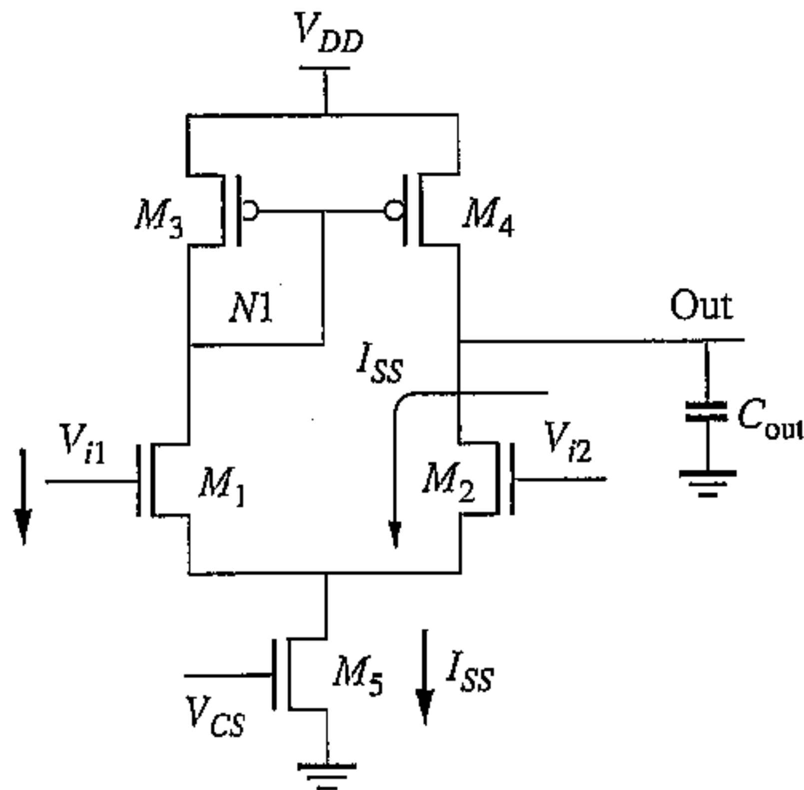


Differential Voltage Sense Amp

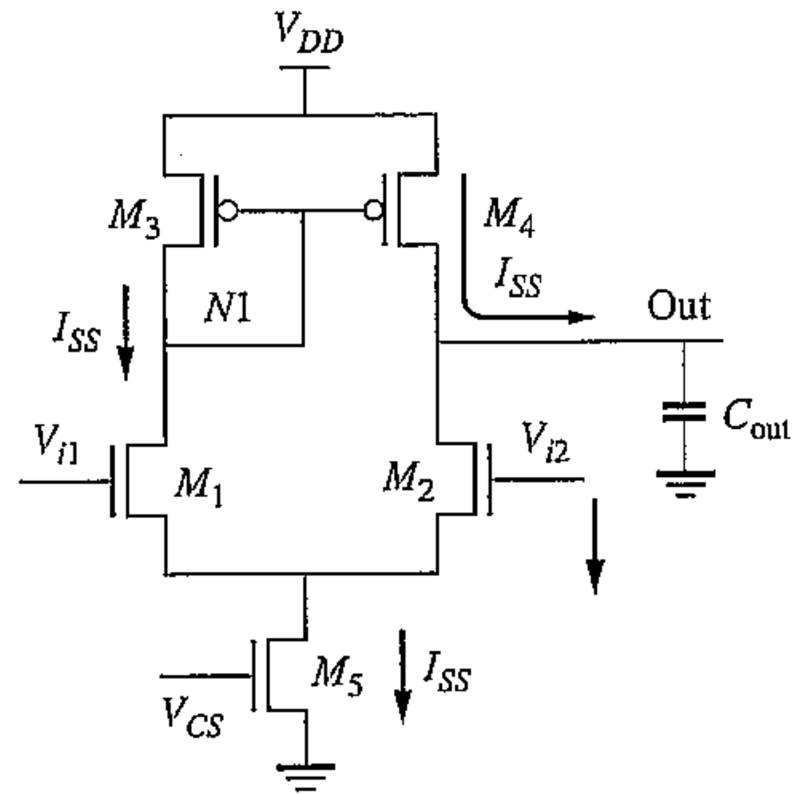
Consists of:
- common source amp
- current mirror
- current biasing

Advantages:
- High Speed Operation
- Good noise immunity
- high CMRR

Detection of ‘0’ and ‘1’



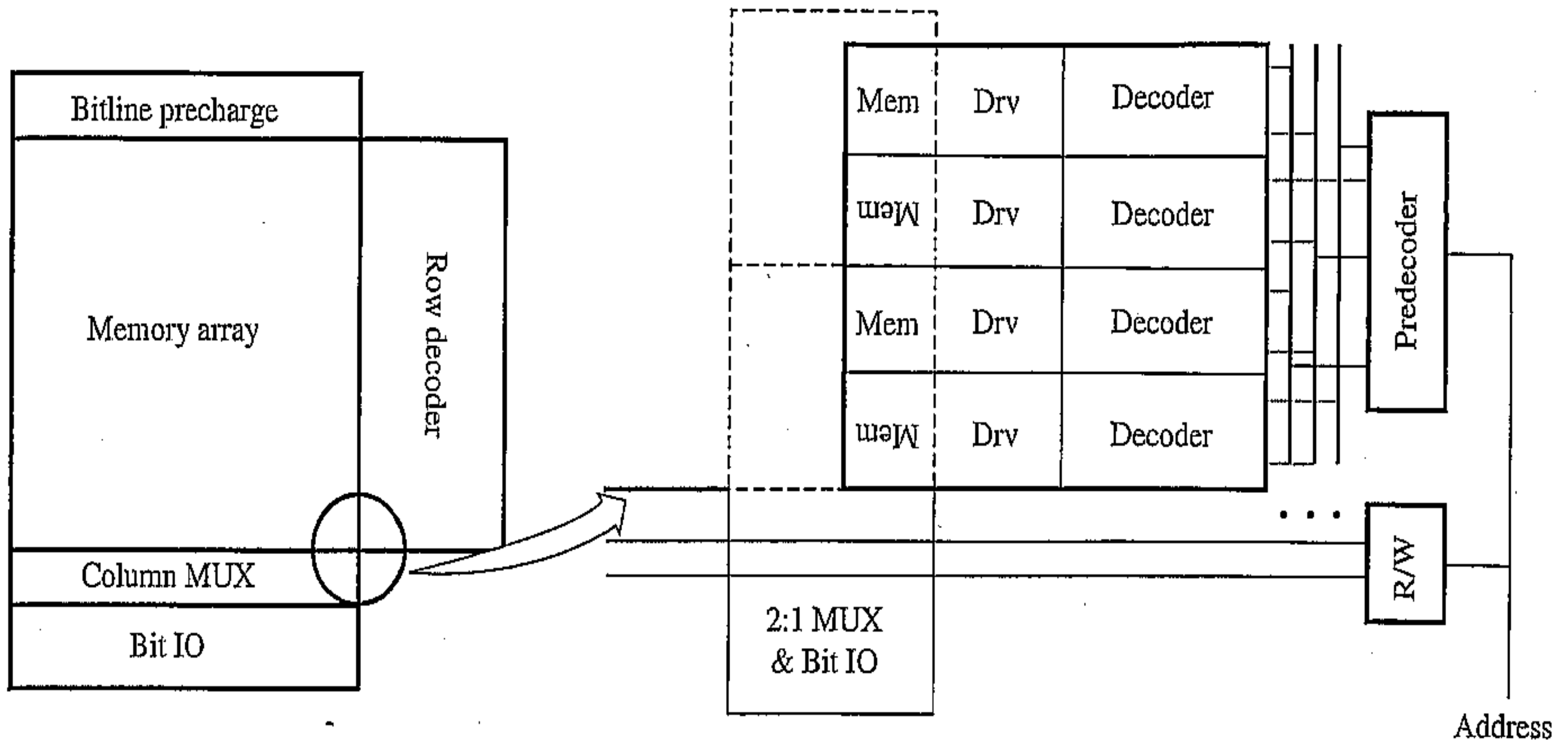
(a) Discharging output



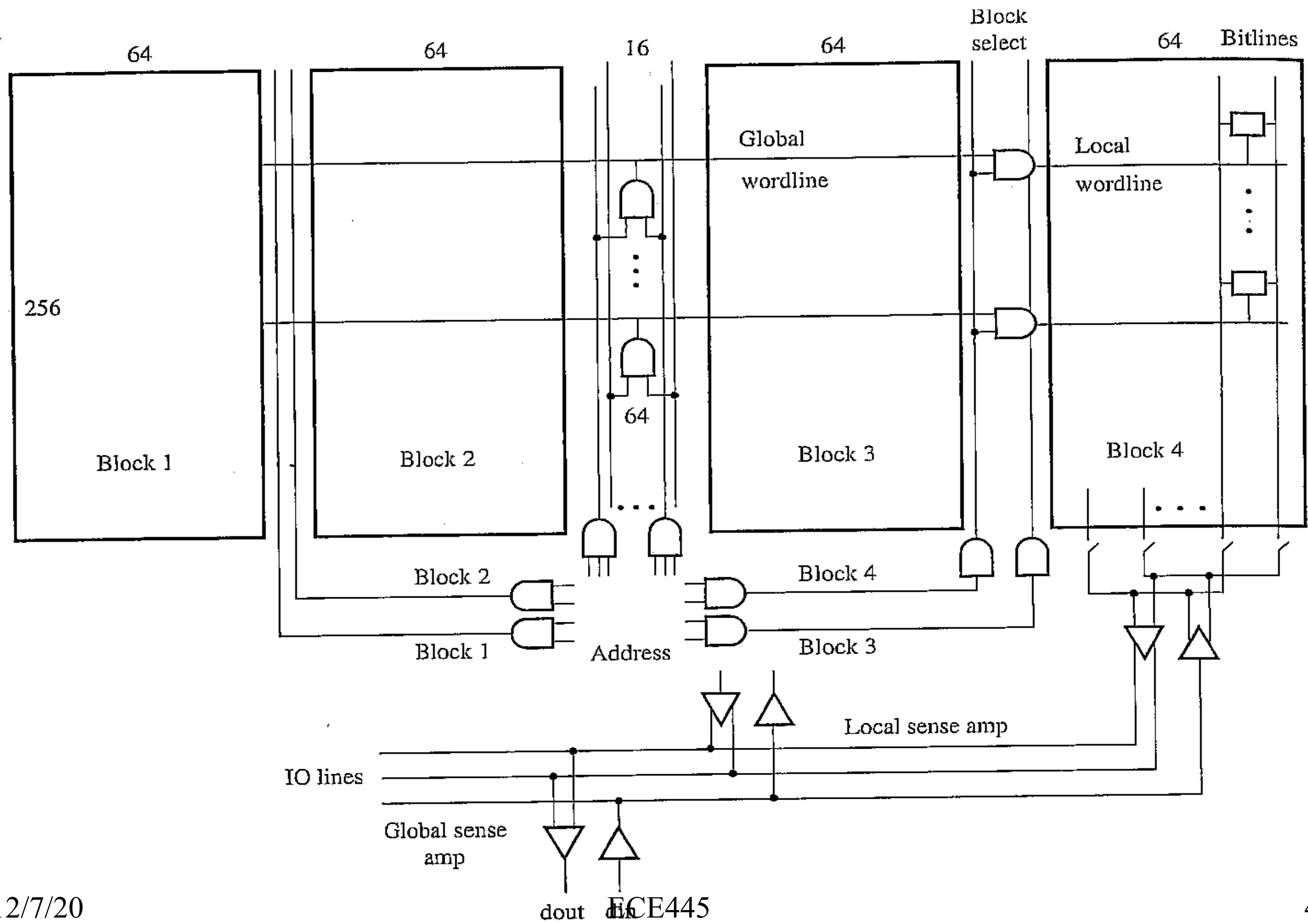
(b) Charging output

Memory Architecture

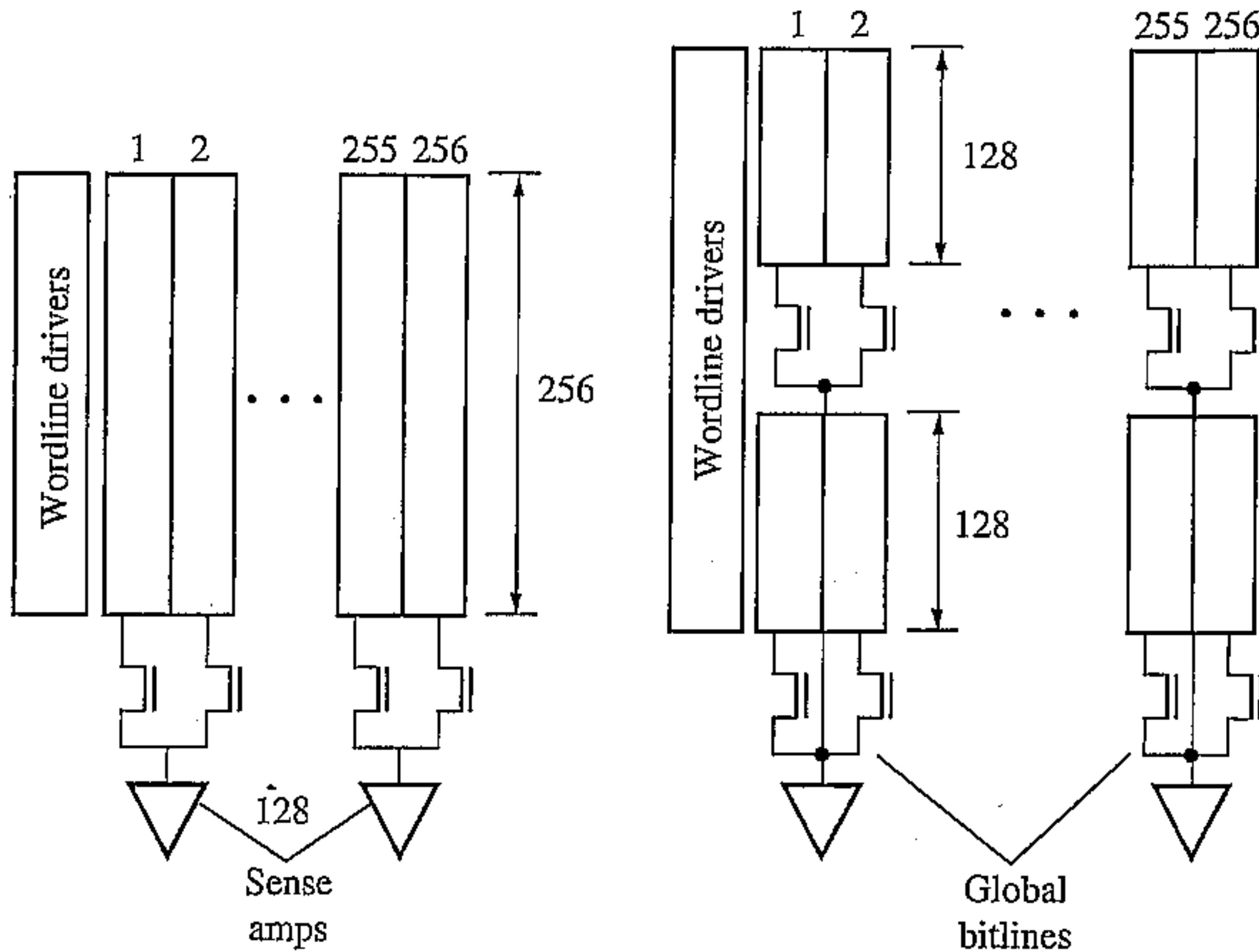
Basic Memory Architecture



Partitioning - Divided Wordline



Partitioning – Divided Bitline



(a) Single-level MUX

(b) Two-level MUX

Applications

Read / Write Non-volatile Memory
- USB memory sticks
- Digital cameras
- MP3 players
- …

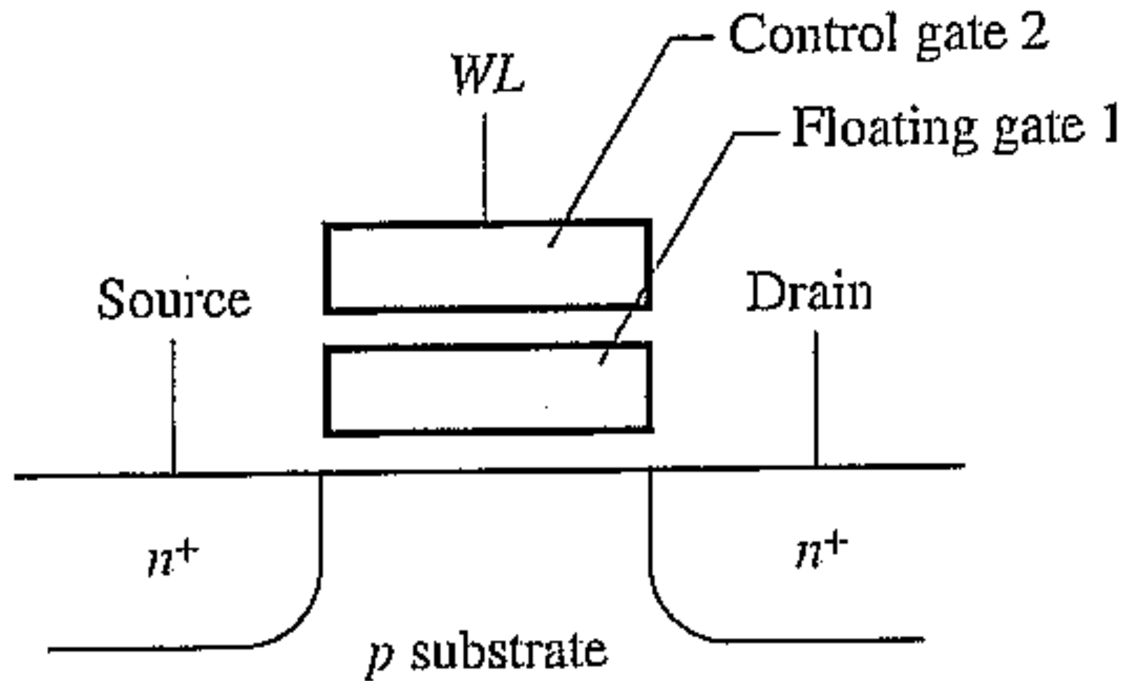
10^5 R/W operations

1T cell implementation of E^2PROM

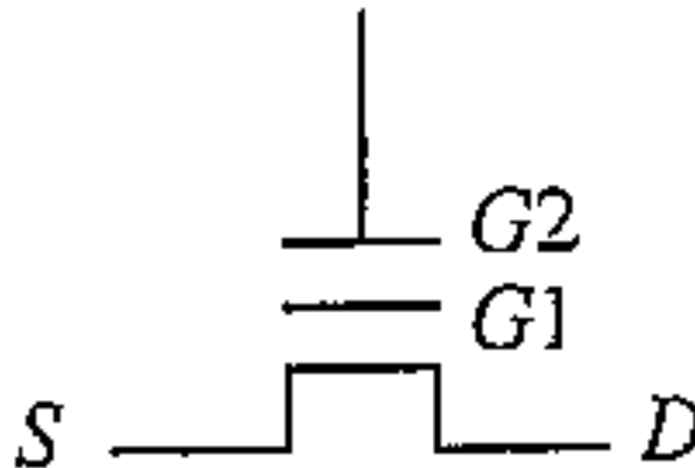
Two architectures
- NAND
- NOR

Flash Memory

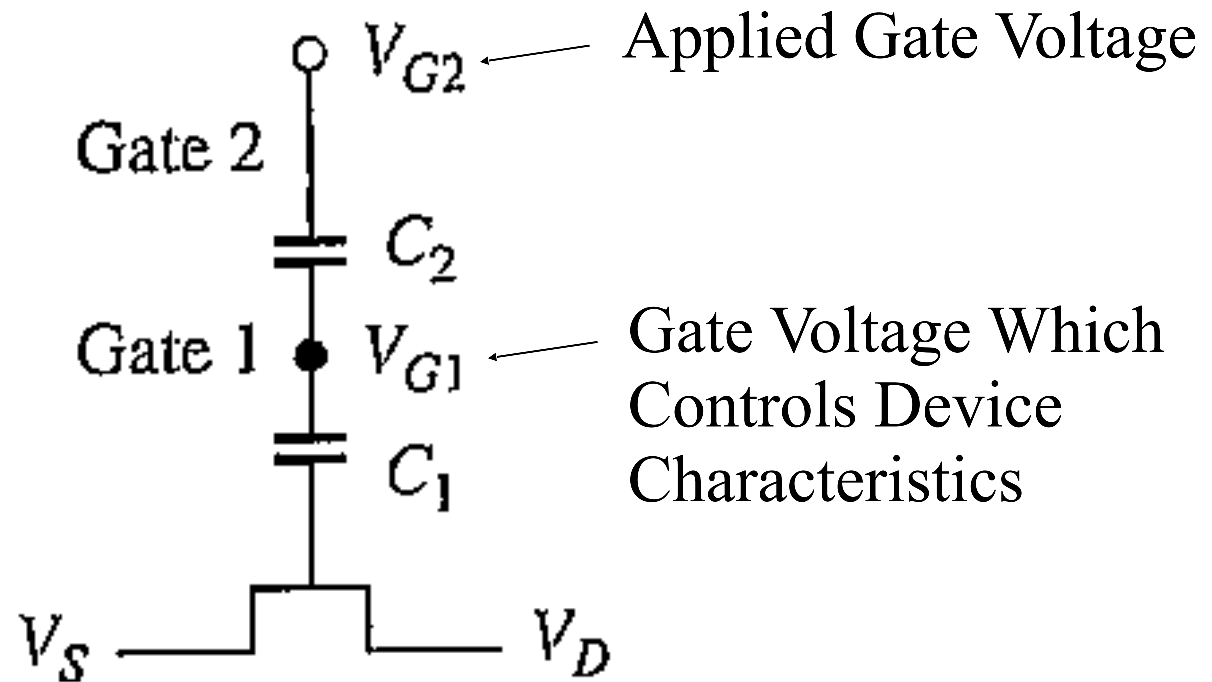
Dual-Gate Structure



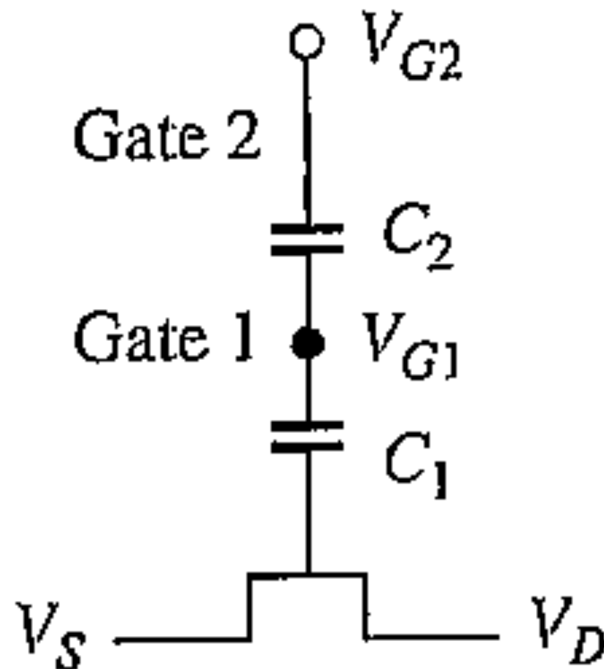
Symbol



Schematic Representation

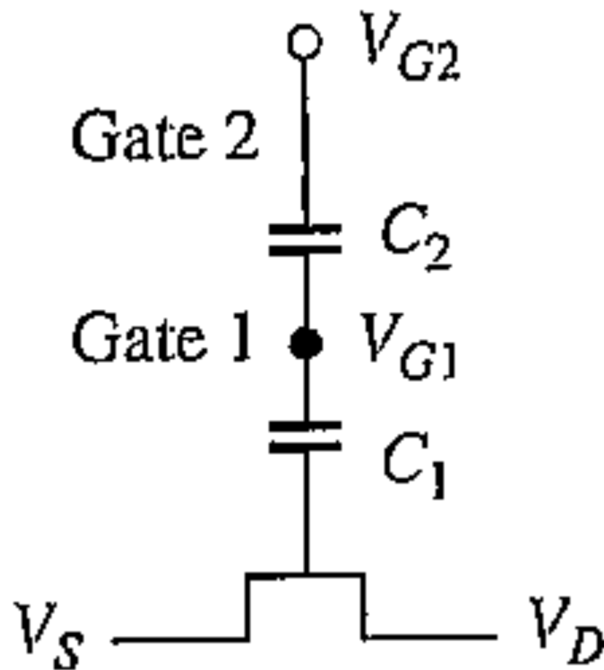


Capacitive Divider at Gate



$$\Delta V_{G1} = \Delta V_{G2} \frac{C_2}{C_1 + C_2}$$

To Turn The Device On

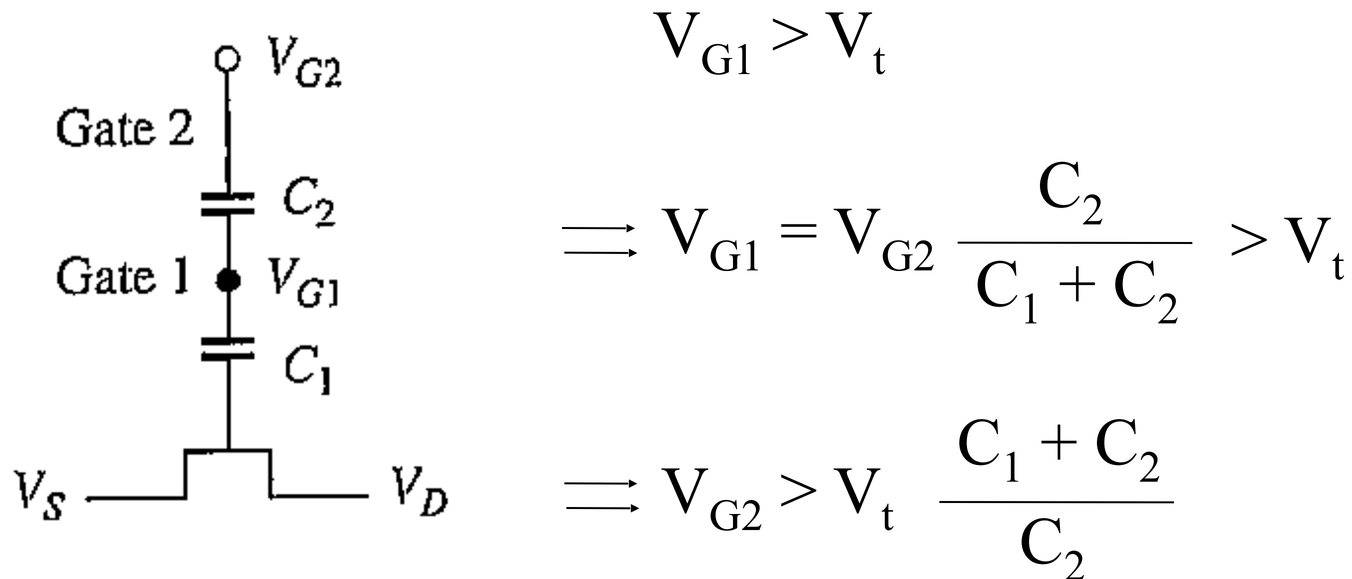


$$V_{G1} > V_t$$

$$\Rightarrow V_{G1} = V_{G2} \frac{C_2}{C_1 + C_2} > V_t$$

$$\Rightarrow V_{G2} > V_t \frac{C_1 + C_2}{C_2}$$

Device Operation



$$V_{G1} > V_t$$

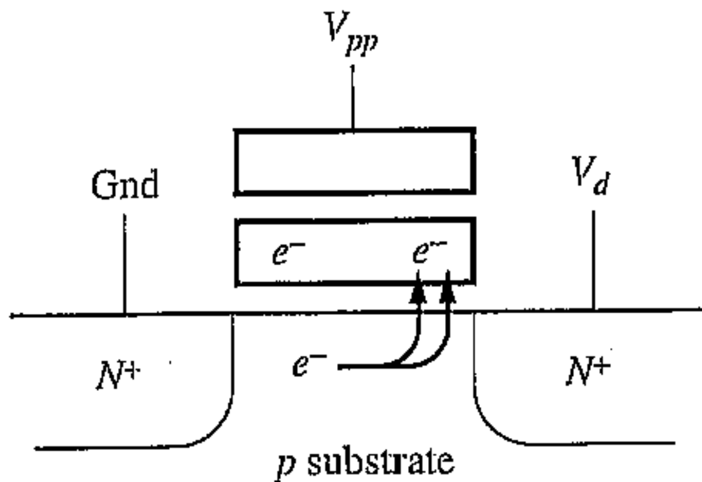
$$\Rightarrow V_{G1} = V_{G2} \frac{C_2}{C_1 + C_2} > V_t$$

$$\Rightarrow V_{G2} > V_t \frac{C_1 + C_2}{C_2}$$

Device operation relies on the ability to store and remove charge from the floating gate → namely node V_{G1}

Write Process

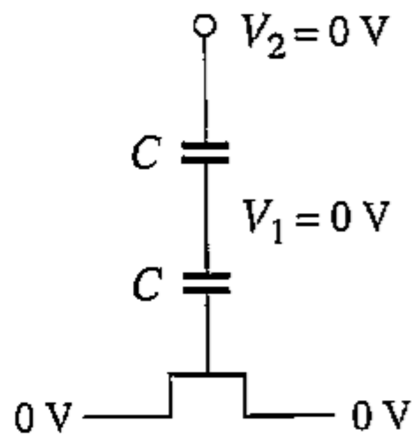
Write process relies on "Hot Carrier Injection" (HCL)



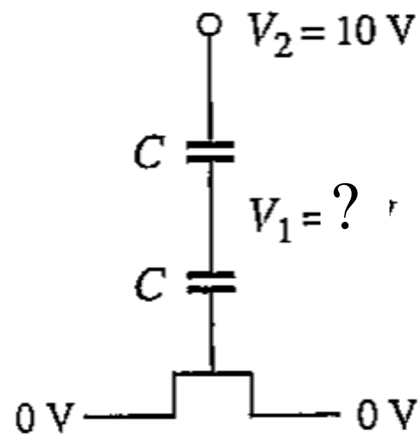
- Raise V_{G2} and V_{DS} >> VDD
- Avalanche breakdown of Drain/Substrate Junction
- Electrons are injected through the gate oxide onto the floating gate
- Self-terminating process because V_{G1} decreases as electrons are injected onto the floating gate

Example

Assume C1 = C2 = C
VDD = 5V, V_T = 1V



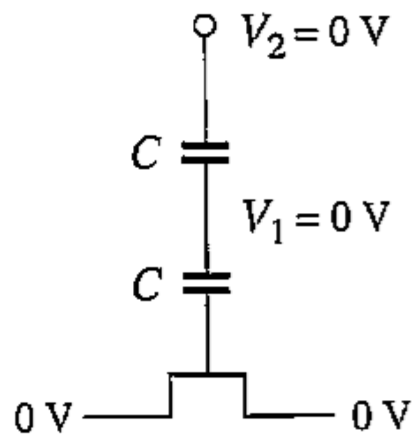
(a) Initial state



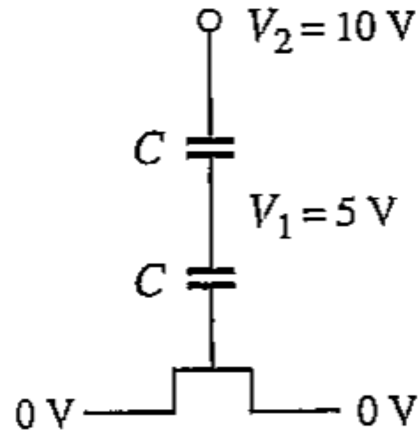
(b) After applying 10 V

Example

Assume C1 = C2 = C
VDD = 5V, V_T = 1V



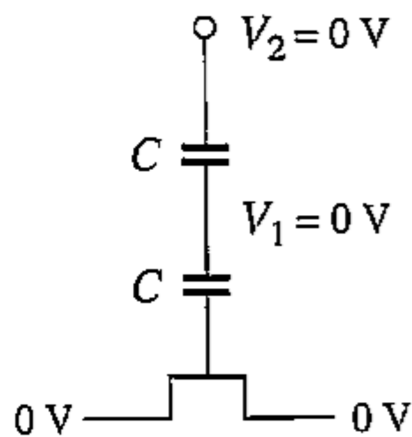
(a) Initial state



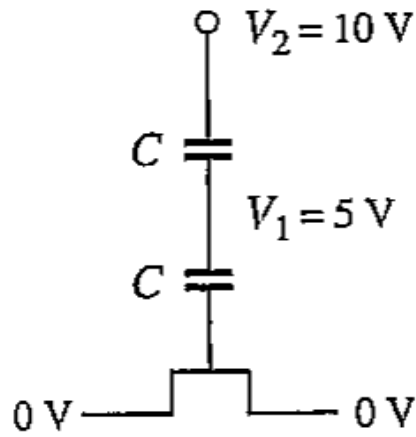
(b) After applying 10 V

Example

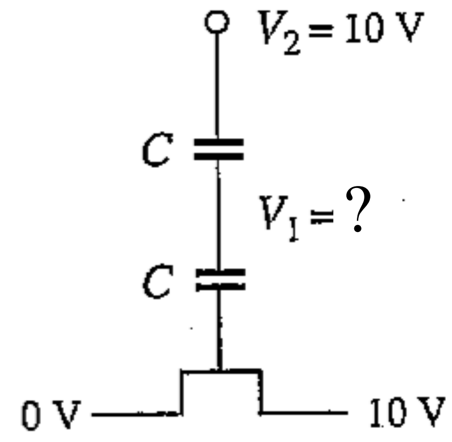
Assume C1 = C2 = C
VDD = 5V, V_T = 1V



(a) Initial state



(b) After applying 10 V

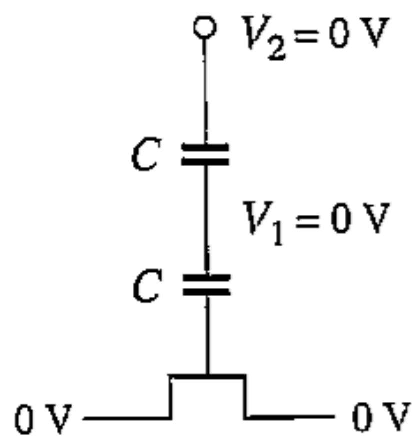


(c) After programming

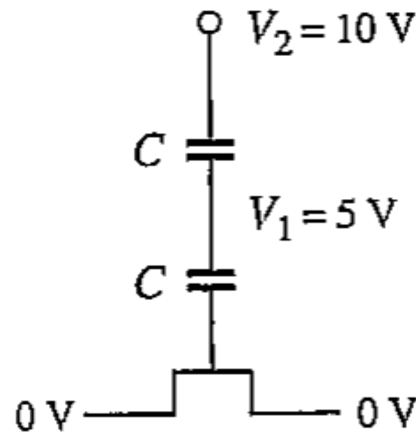
Program by applying V_{DS} = 10V

Example

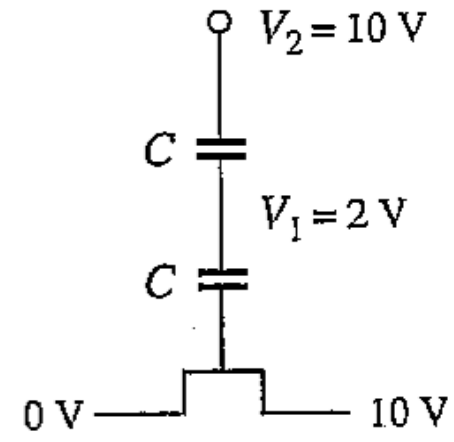
Assume C1 = C2 = C
VDD = 5V, V_T = 1V



(a) Initial state



(b) After applying 10 V



(c) After programming

Program by applying V_{DS} = 10V
Assume V_{G1} drops to 2V

Example

Assume C1 = C2 = C
VDD = 5V, V_T = 1V

V_2 = 10 V

C

V_1 = 2 V

C

0 V 10 V

(c) After programming

V_2 = 0V

C

V_1 = ?

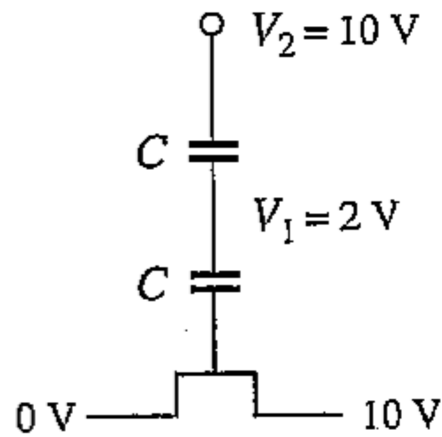
C

0 V 10 V

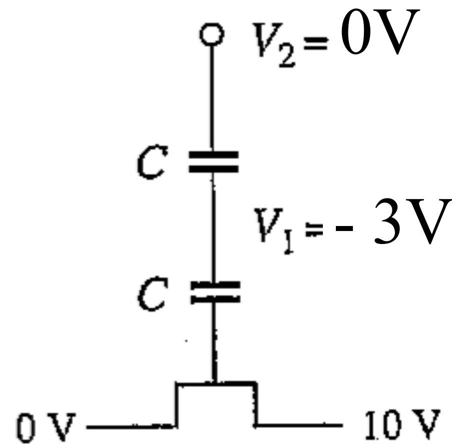
Reduce gate voltage V_{G2} = 0V

Example

Assume C1 = C2 = C
VDD = 5V, V_T = 1V



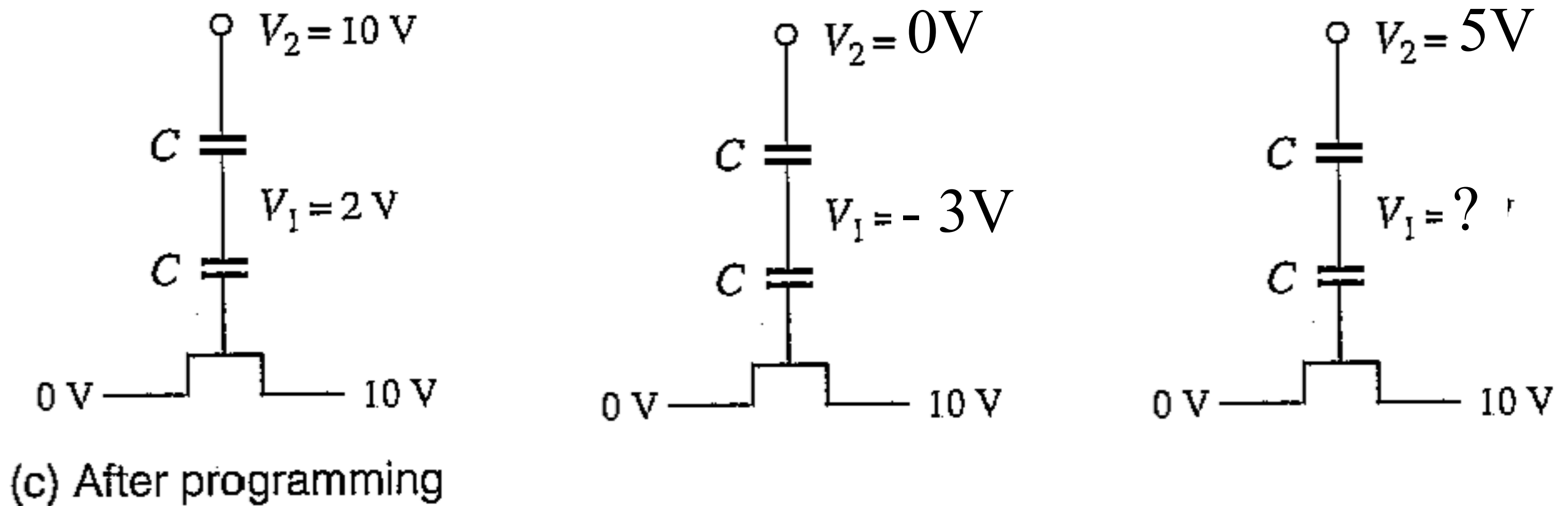
(c) After programming



Reduce gate voltage V_{G2} = 0V

Example

Assume C1 = C2 = C
VDD = 5V, V_T = 1V

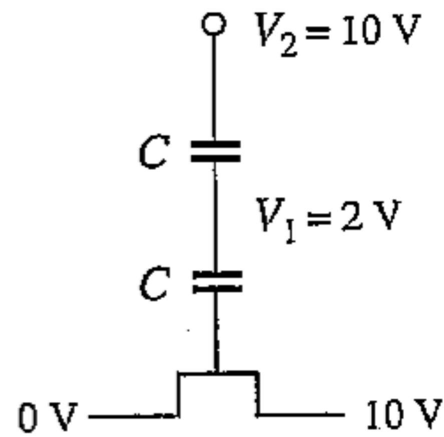


(c) After programming

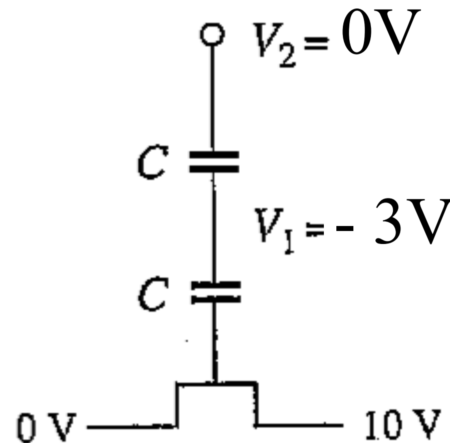
Raise gate voltage V_{G2} = VDD

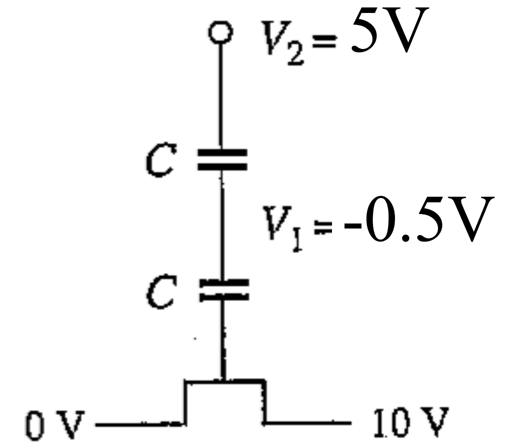
Example

Assume C1 = C2 = C
VDD = 5V, V_T = 1V



(c) After programming

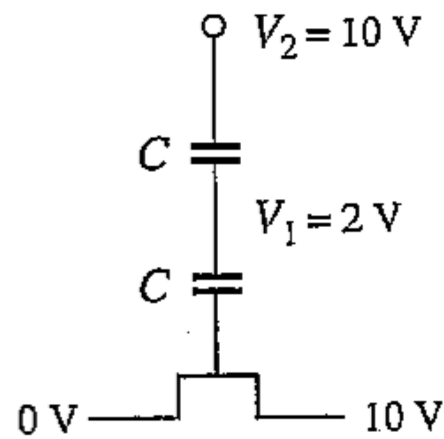




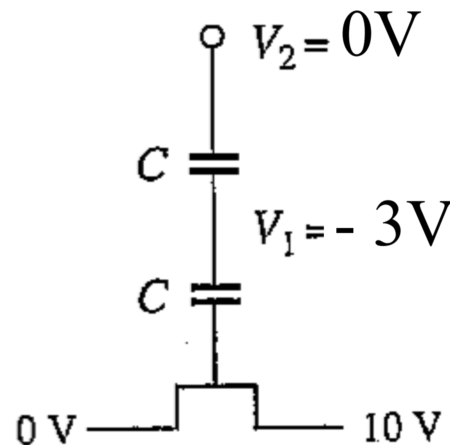
Raise gate voltage V_{G2} = VDD
TRANSISTOR IS STILL OFF!!
Have written a "1"

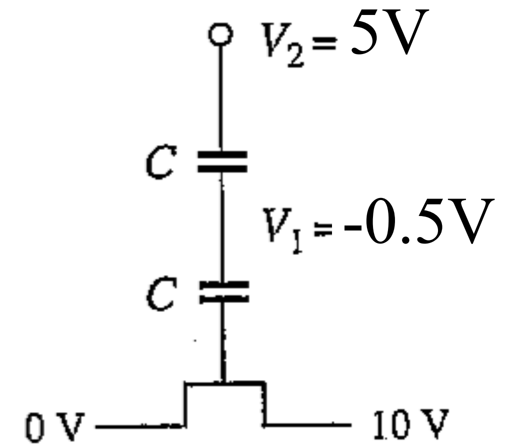
Example

Assume C1 = C2 = C
VDD = 5V, V_T = 1V



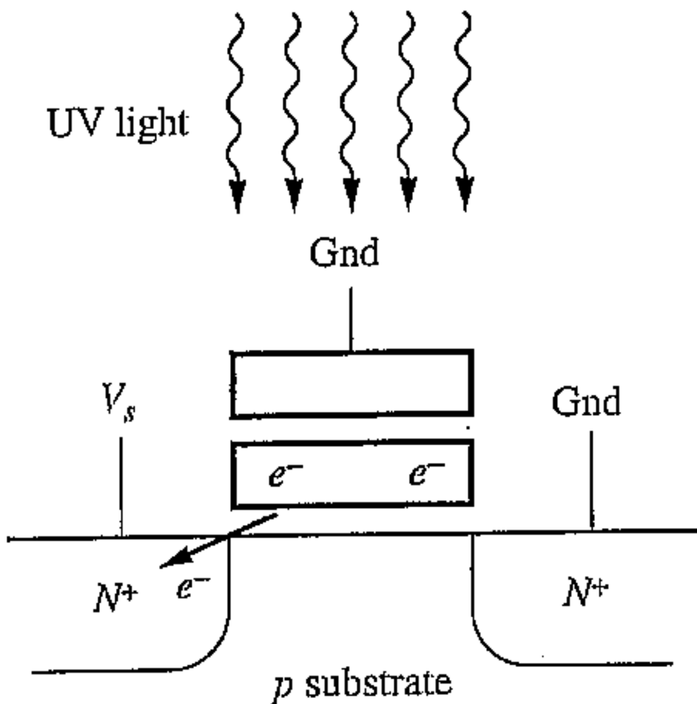
(c) After programming





Raise gate voltage V_{G2} = VDD
TRANSISTOR IS STILL OFF!!
To turn the transistor on: V_{G2} = 8V

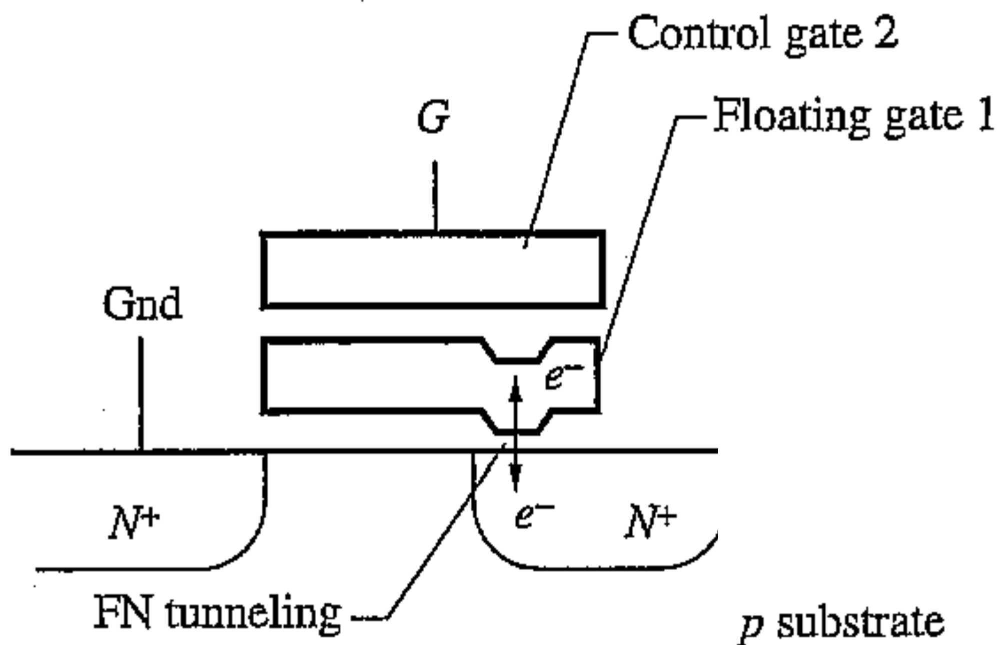
Different Methods to Erase



(b) Erase process —UV light

In a conventional EPROM, UV light is used generate e/h pairs in the SiO_2 dielectric making the dielectric conductive

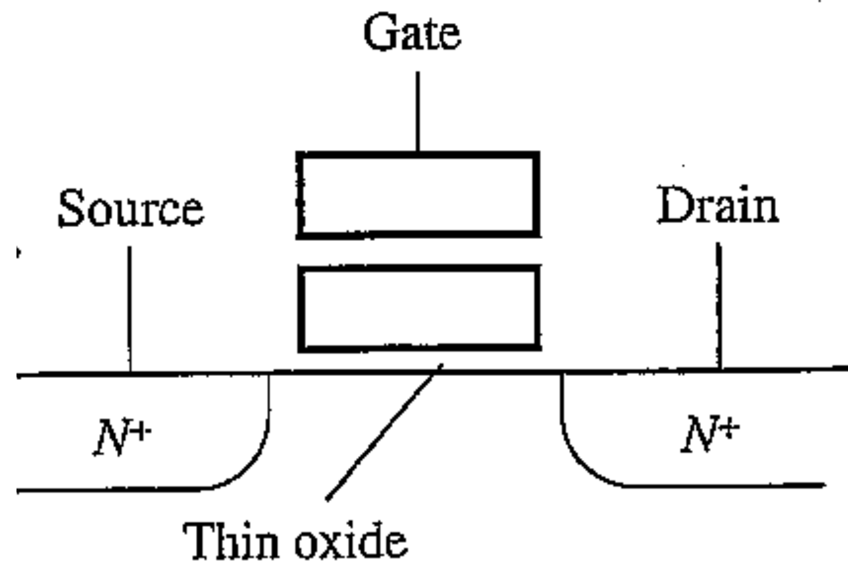
Different Methods to Erase



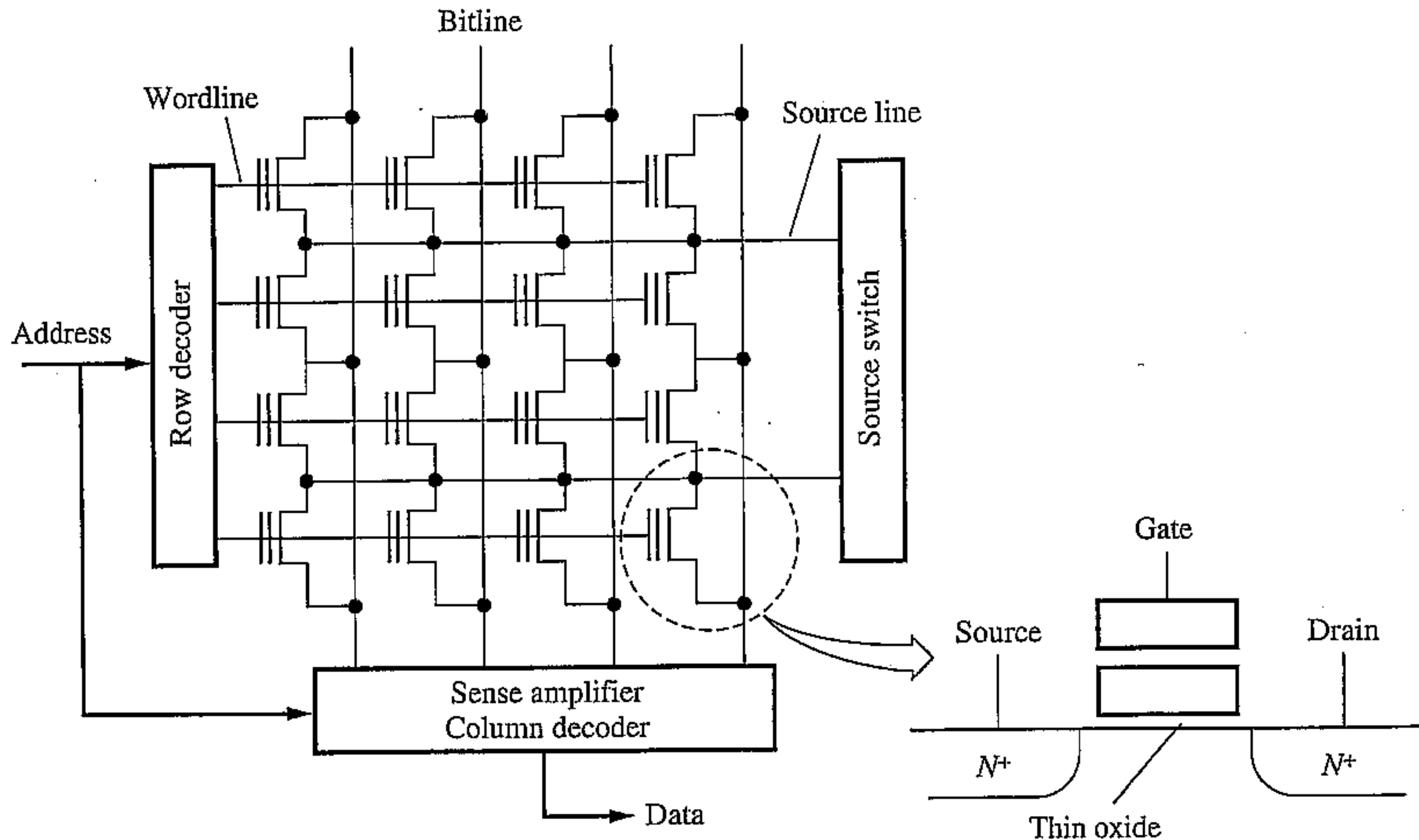
In a E2PROM, the charge is removed by "Fowler-Nordheim" (FN) transport.

When the field across the oxide exceed ~10 MV/cm, electrons can tunnel across the oxide

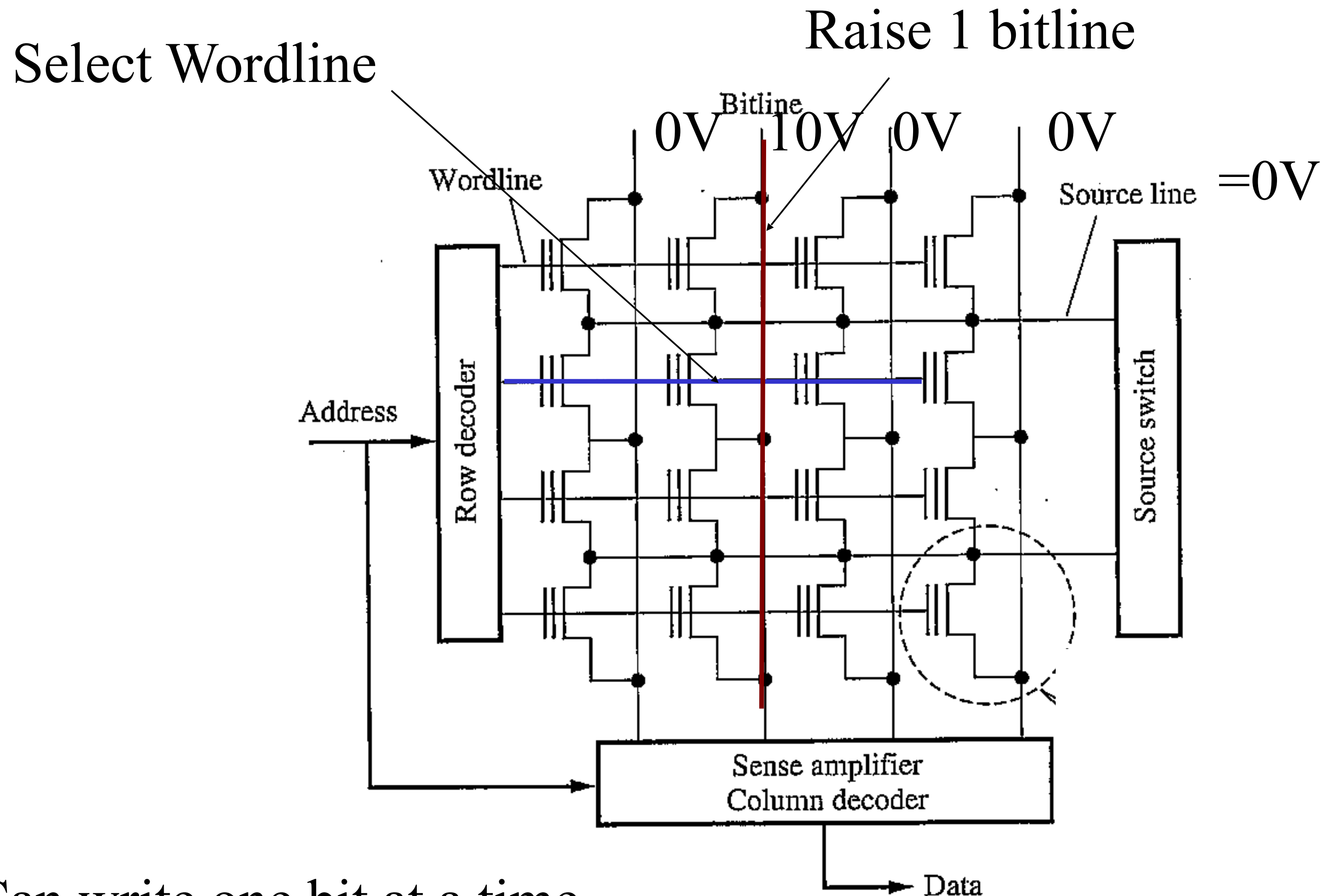
1T Cell - FLASH



NOR Array



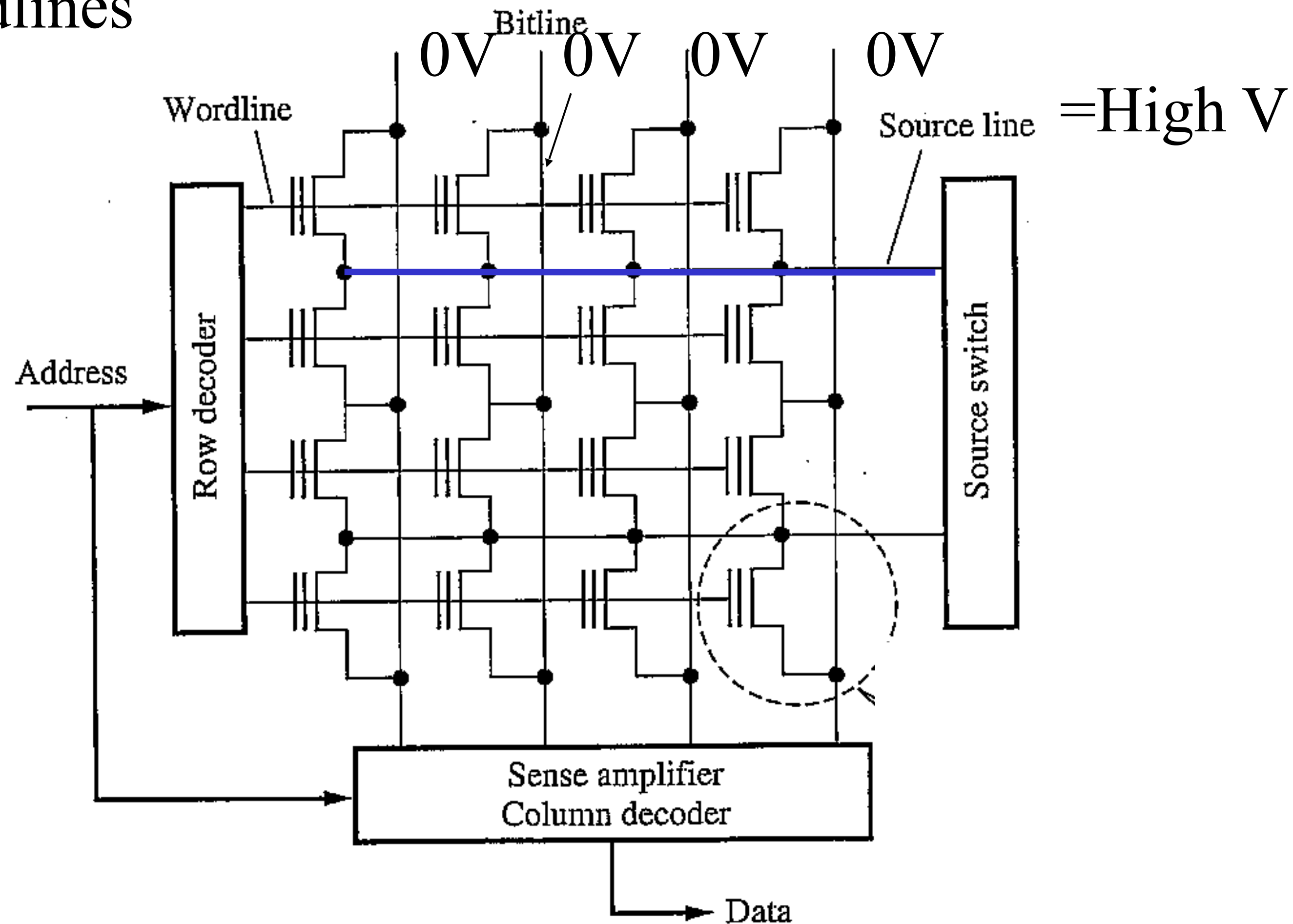
Write – "hot carrier injection"



Can write one bit at a time

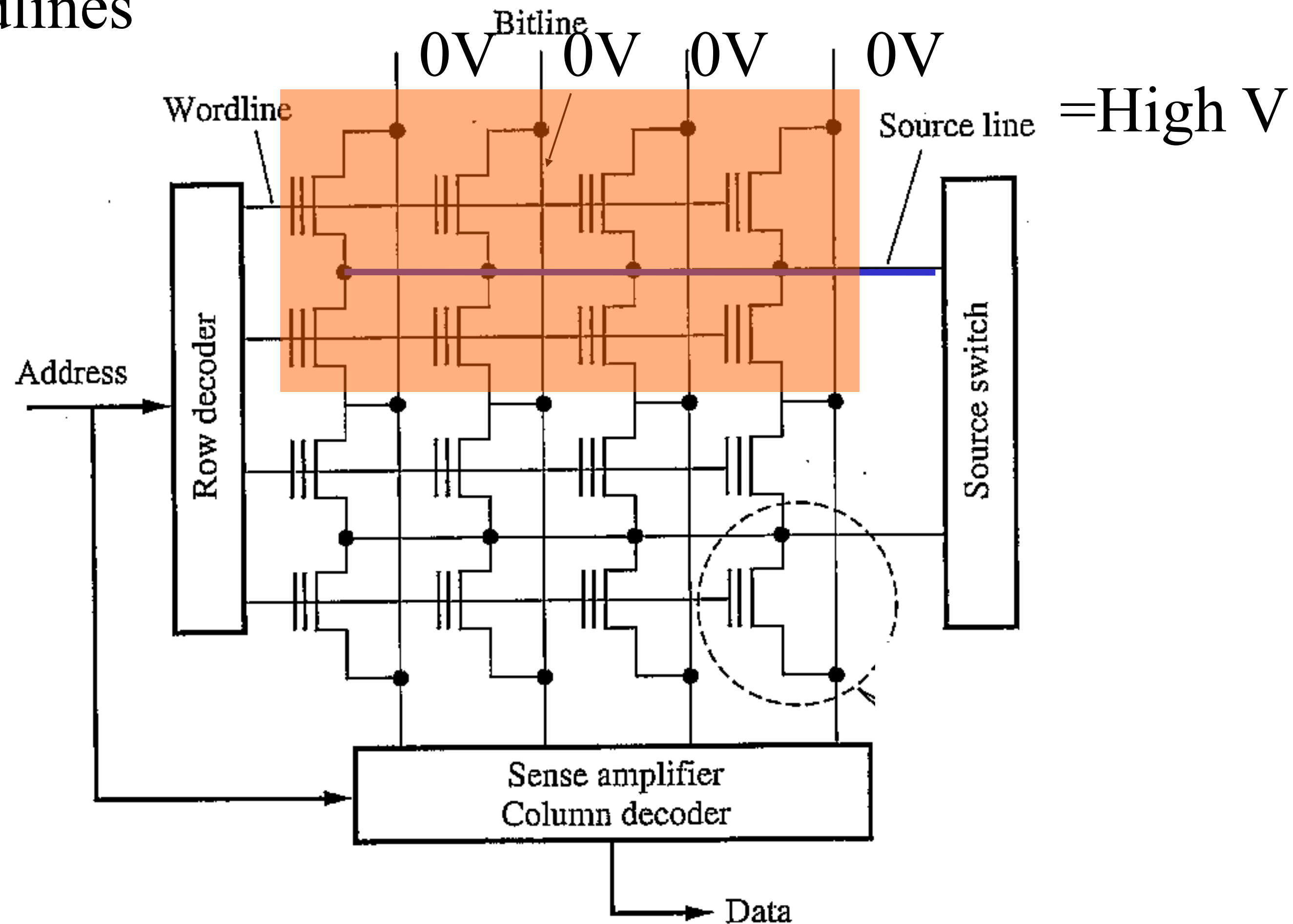
Erase – "Fowler-Nordheim Tunneling"

0V on Wordlines



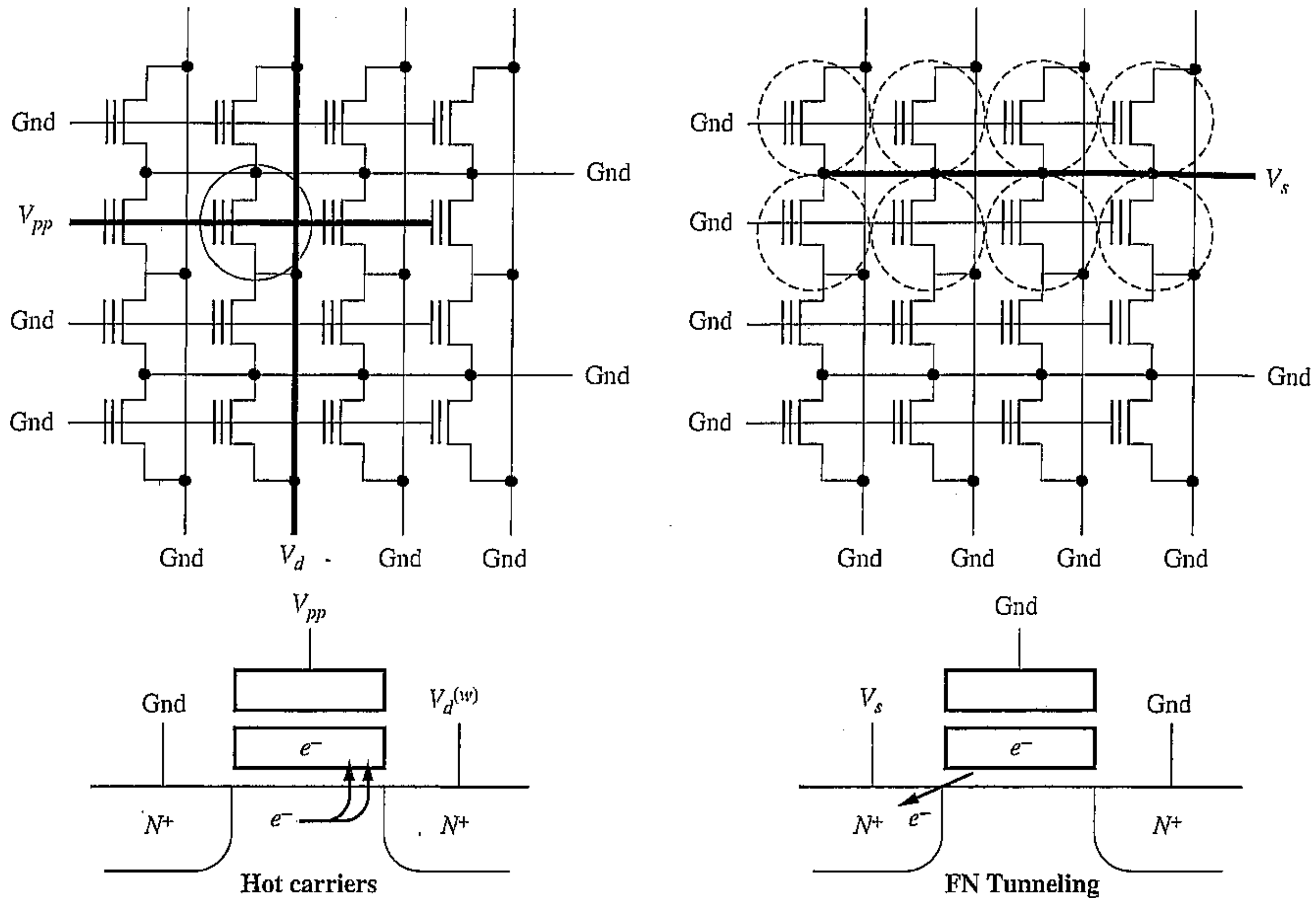
Erase – “Fowler-Nordheim Tunneling”

0V on Wordlines



All transistors connected to the source line are erased simultaneously → FLASH

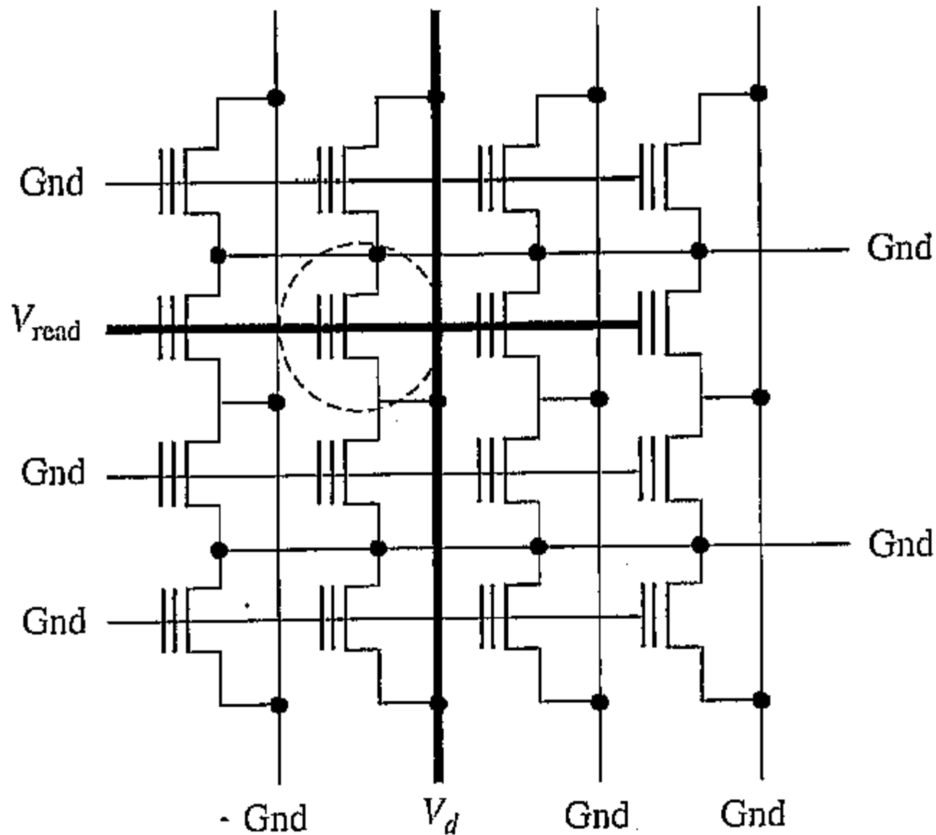
Write / Erase

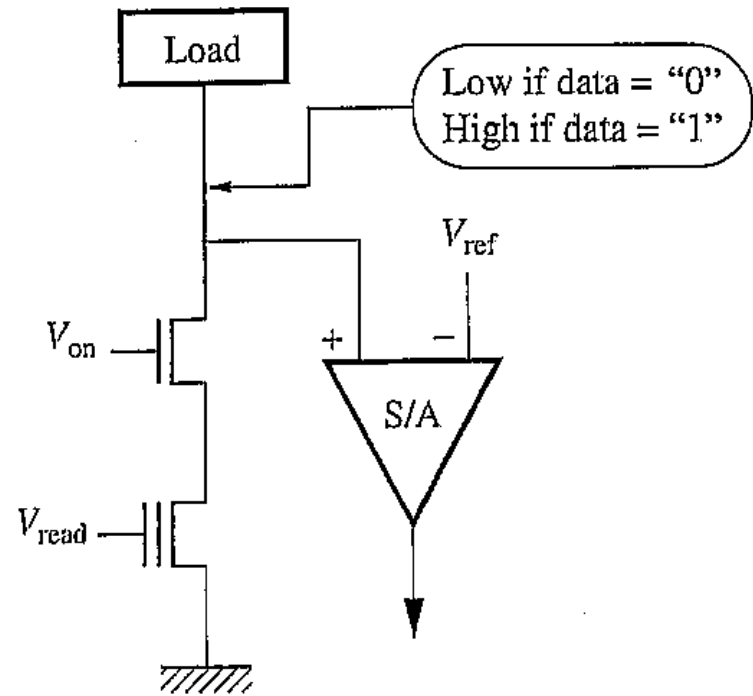


(a) Write operation

(b) Erase operation (blockwise only)

Read Operation



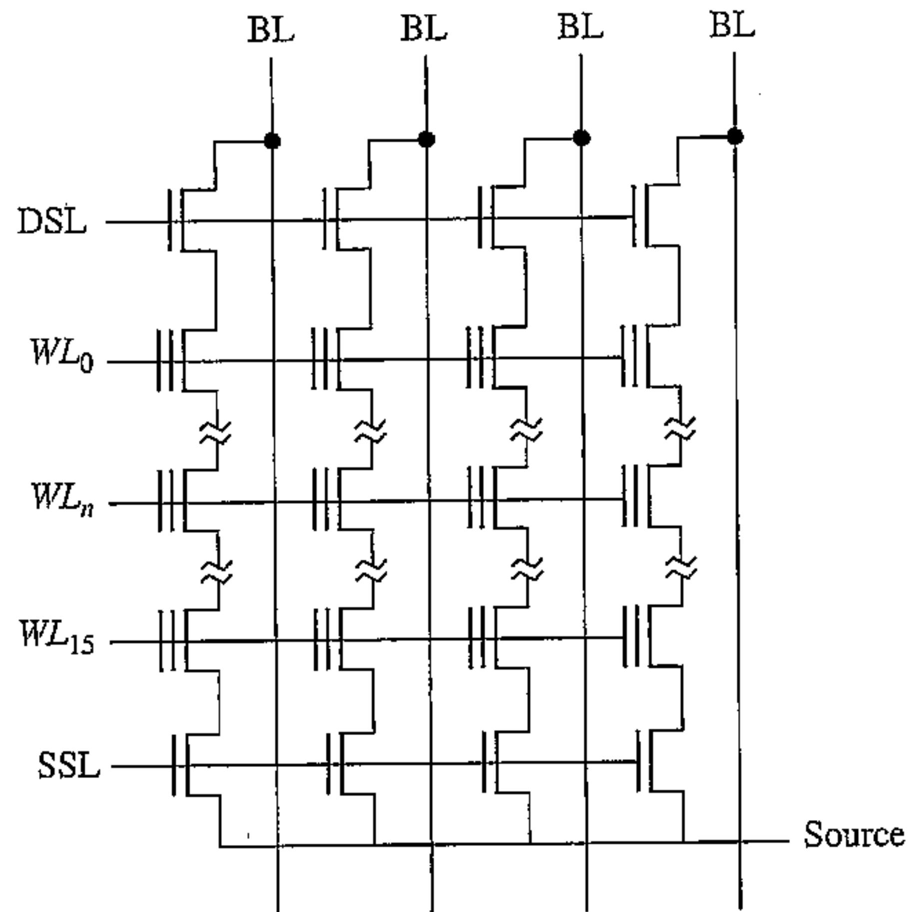


Precharge bitline
Source line → Gnd
Enable wordline

NAND vs NOR Arrays

	Write	Read	Erase	Density
NAND	Fast	Slow	Fast	High
NOR	Slow	Fast	Slow	Low

NAND Flash Array



Issues

Read / Write Endurance
- > 10^5 Operations

Redundancy for improved yield

Multi-Bit Cell Architectures – in common practice today!